

IEEE SW Test Workshop

Semiconductor Wafer Test Workshop



*Rocky J.M.Lee, J.S.Choi, IMT Co Ltd, Korea

J.H.Park, Willtechnology Co. Ltd, Korea

Probe Card Cleaning by Laser



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- PC cleaning Issues & Needs
- Conventional cleaning & problems
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- Advantages of laser cleaning
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- Laser cleaning systems
- Summary & Conclusions
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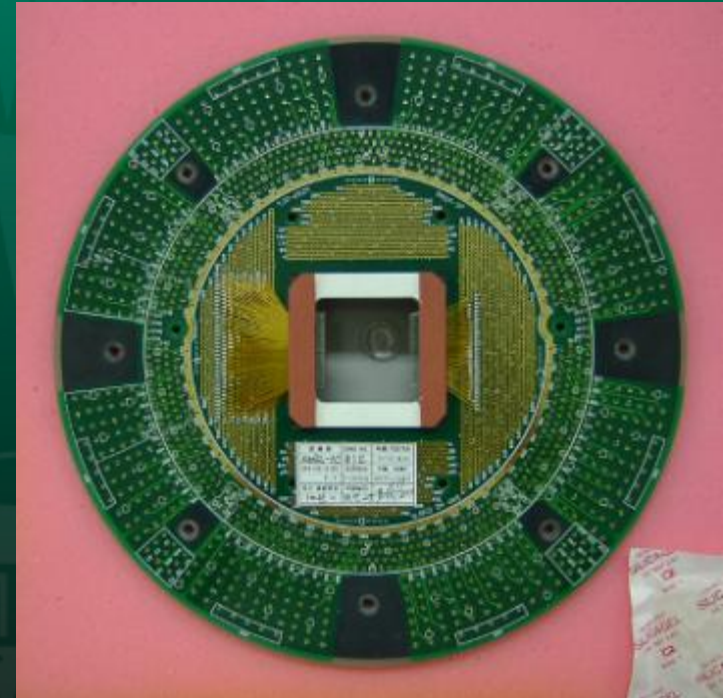


Key Issues & Needs

- Issues
 - : Tip Contamination in Fine pitch or MEMS probe
 - 1. Rc increase > poor contact
 - 2. Leakage occurrence

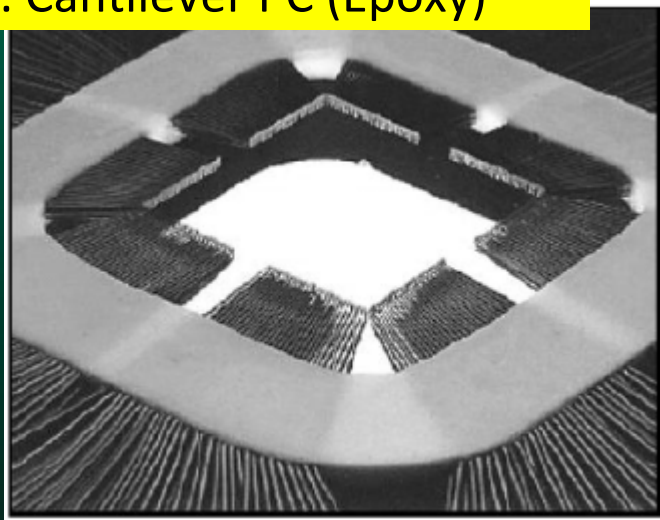
=> Yield drop
- Needs
 - 1. Precise cleaning tool
 - 2. Damage free cleaning tool

=> **Solution : Laser Cleaning**

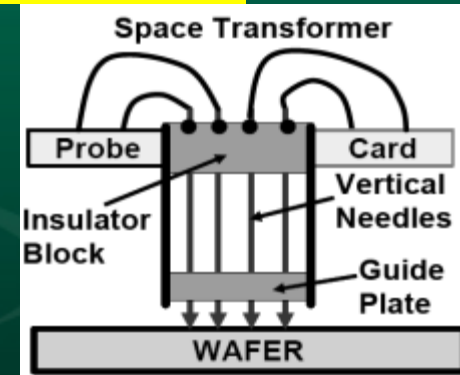


Background - Probe Card Types

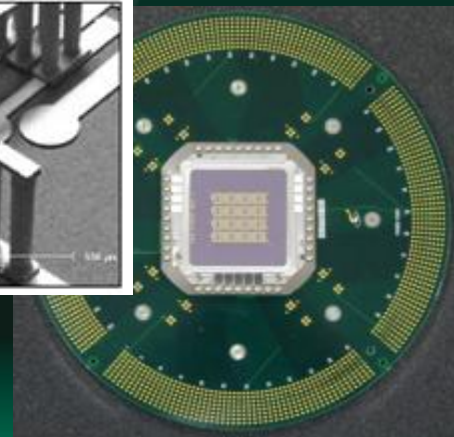
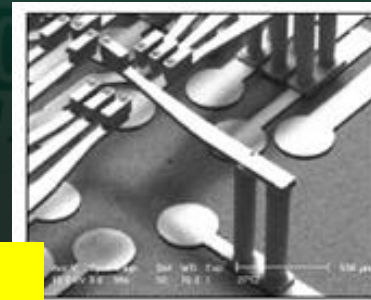
1. Cantilever PC (Epoxy)



2. Vertical PC

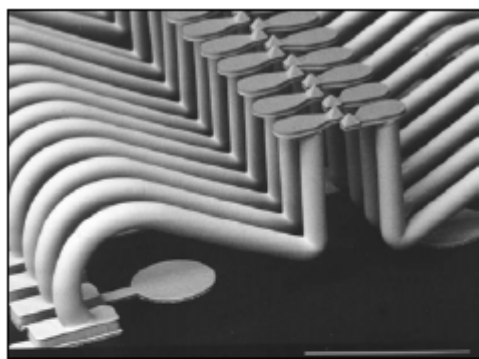


3. MEMS PC

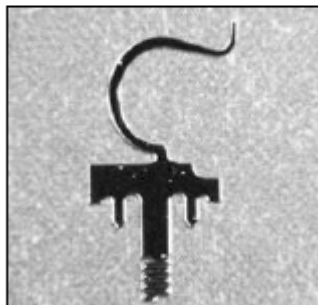


Background - Contactor Shape

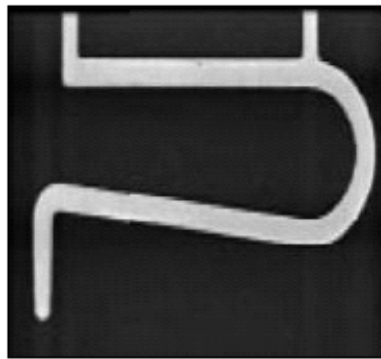
Spring type



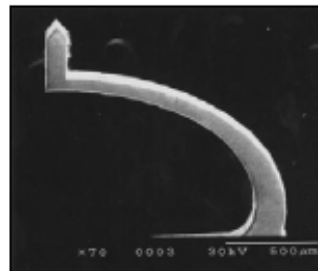
FormFactor



Advantest Labs

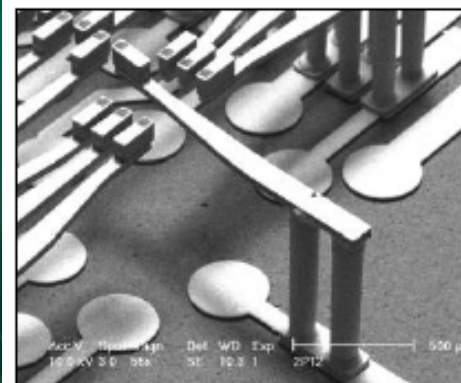


JEM HAWK

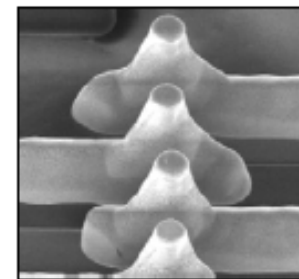


Sumitomo

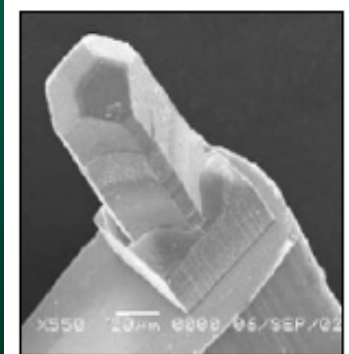
MEMS type



FormFactor



AMST



Phicom



Microfabrica

Conventional Cleaning & Problems

Conventional PC cleaning

: Mechanical contact using abrasive pad at Prober

Problems

1. Difficult to clean the probe sides
2. Probe wear due to contact cleaning => PC Lifetime reduction
3. PC Alignment & planarity change due to contacts => Lifetime red.
4. Consumable Abrasive pads => Extra cost
5. No cleaning solutions for MEMS PC due to delicate structures



***** Effective, No damage & wear, Fast cleaning method required
=> Laser Cleaning**



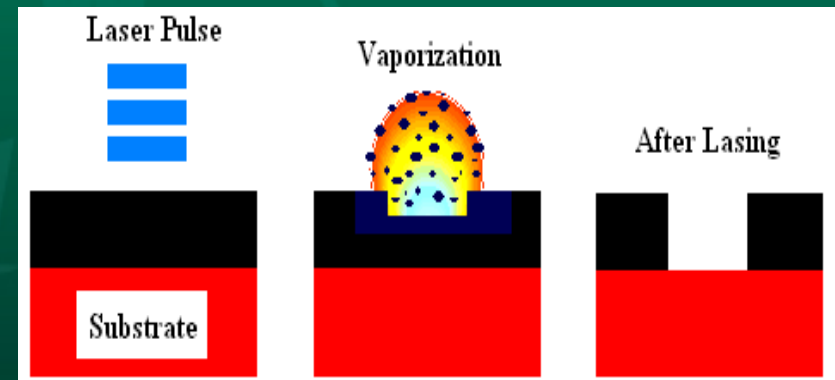
IMT Laser Cleaning

What is a laser cleaning

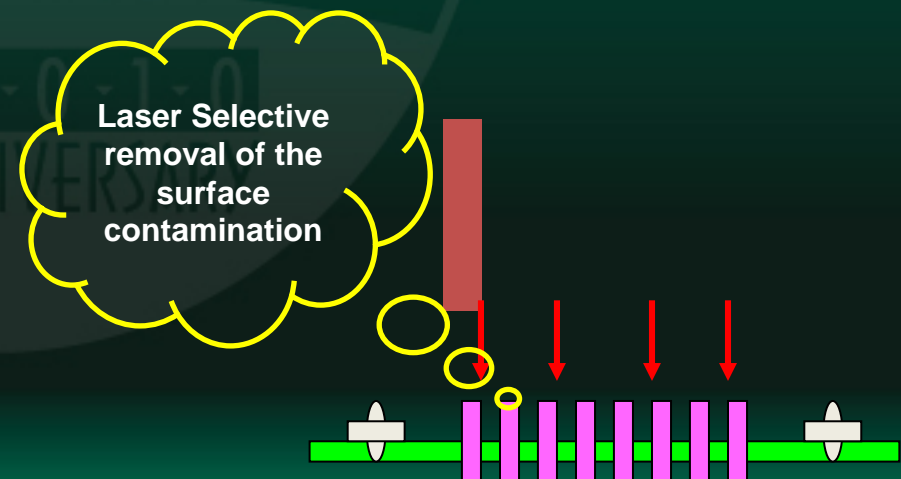
: Dry cleaning technique to remove the surface contamination selectively without inducing any substrate damages by using proper laser beam irradiation

Laser cleaning of probe card

: Various contamination removal process from the probe surface without inducing any substrate damage by using proper laser interactions between laser and contamination. Then enhance the test yield.



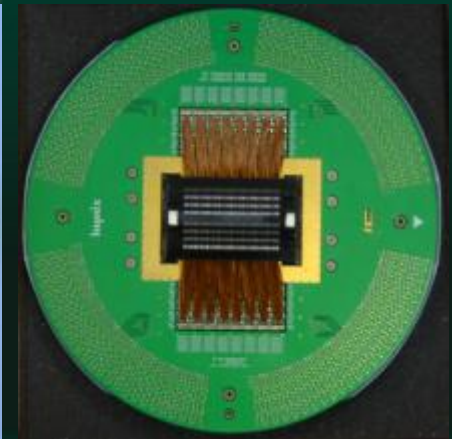
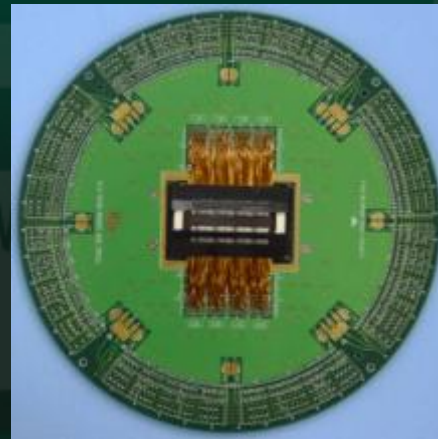
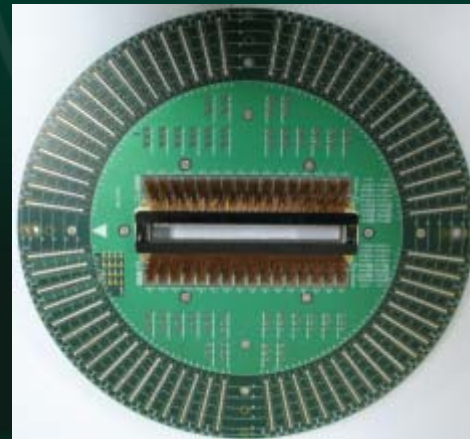
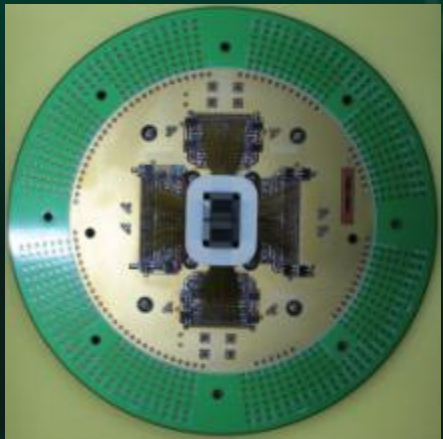
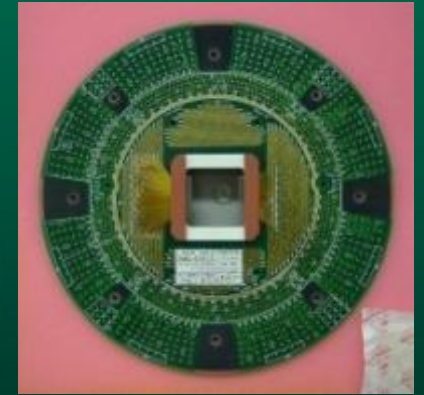
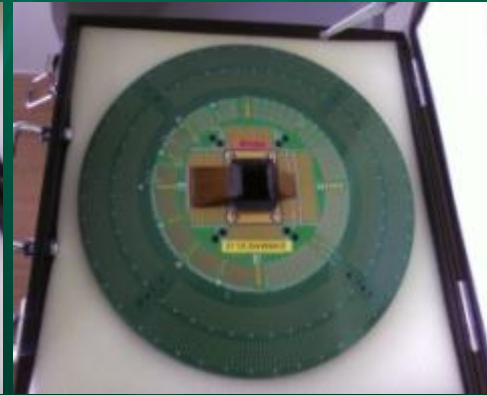
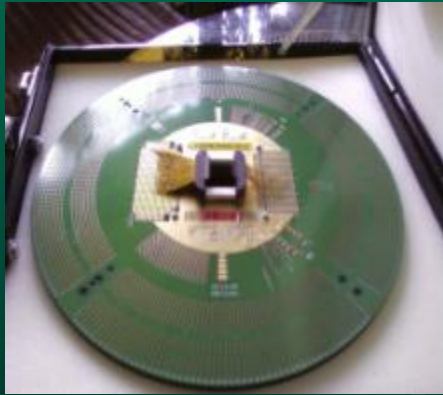
Ref: "Lasers & Cleaning Process", JMLee (2002)



Advantages of Laser Cleaning

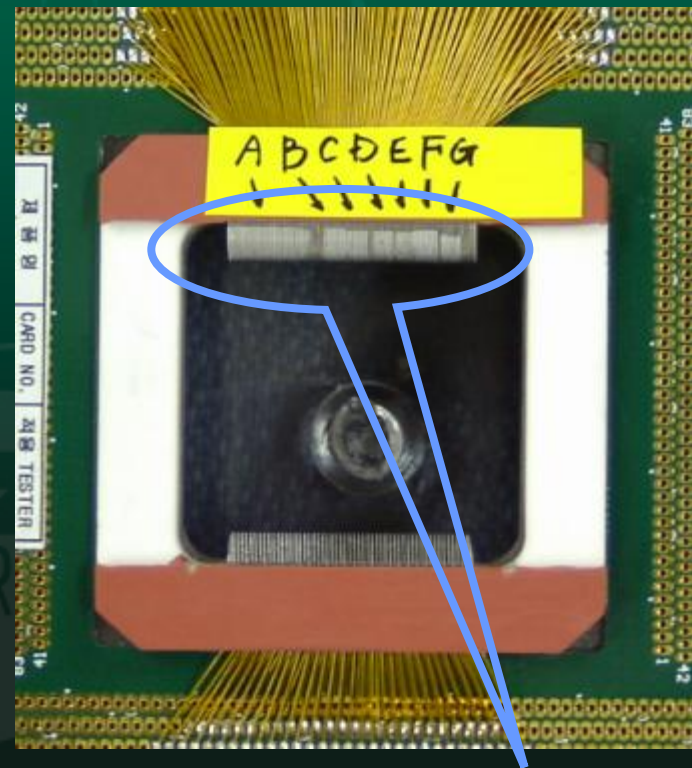
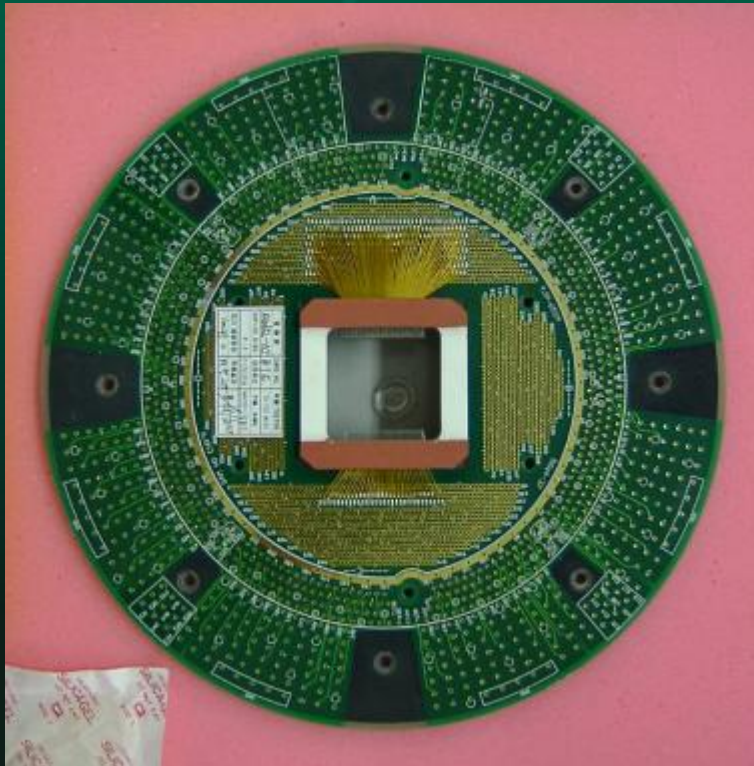
1. **Excellent cleaning performance** by selective removal of only contamination => top & side
2. **No Probe wear** due to non-contact process
3. **Damage free process** due to no physical touch & loads => No planarity & alignment change
4. **Very fast cleaning** process : <10min/300mm one touch PC
5. **Very fast response** process for emergency case
6. **Safe process**: no chemical use and automatic cleaning

Cantilever PCs – W, ReW



Cantilever Type PC

- The Samples before Laser Cleaning

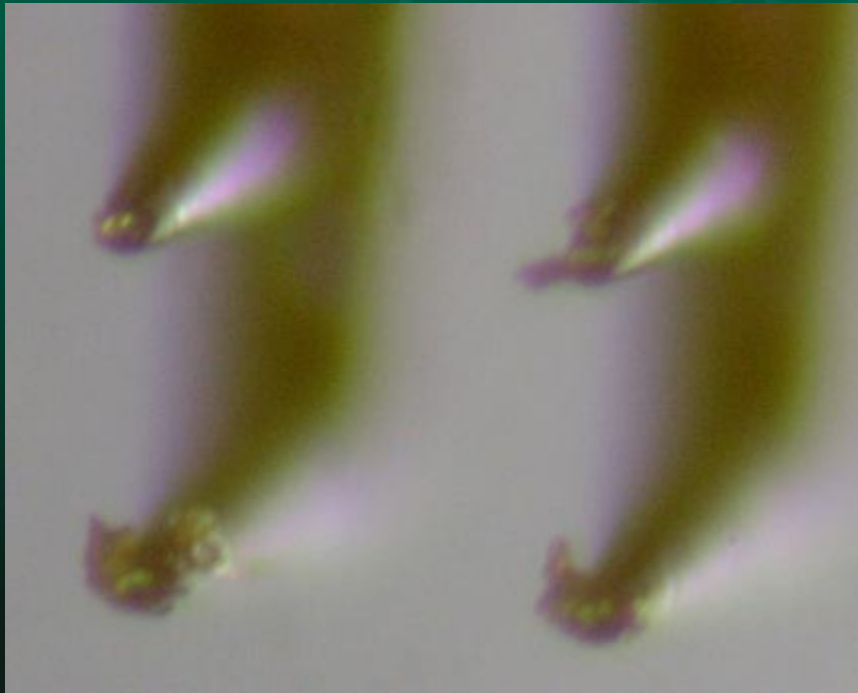


Laser Treated Area

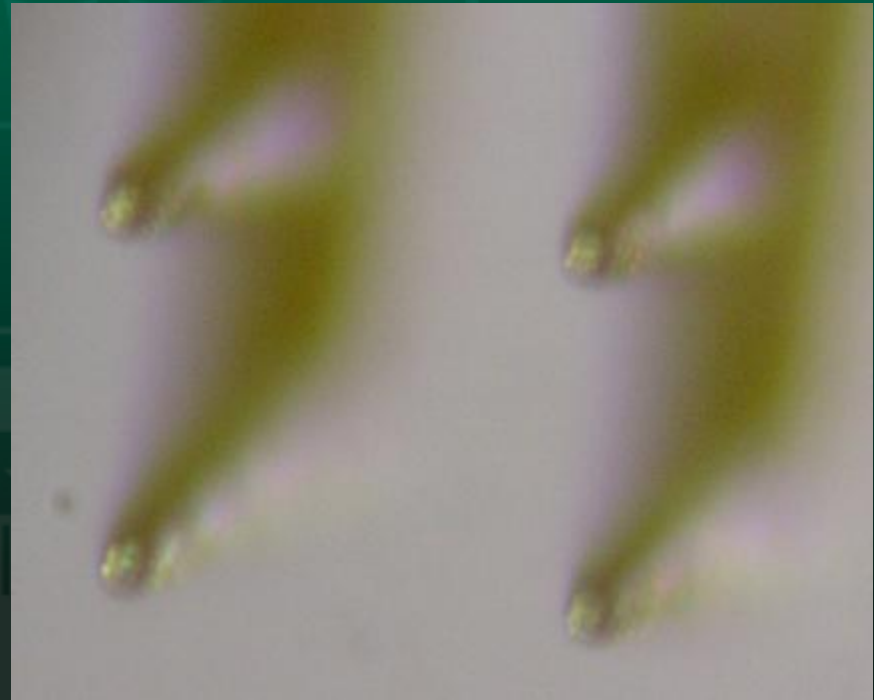


Cleaning Test Result

- Probe Surfaces Before & After Cleaning (x50)



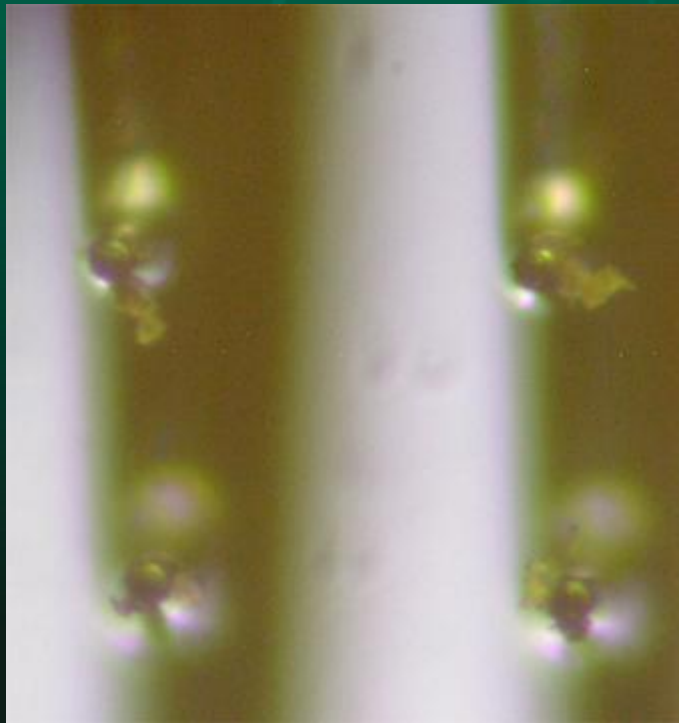
Before Cleaning



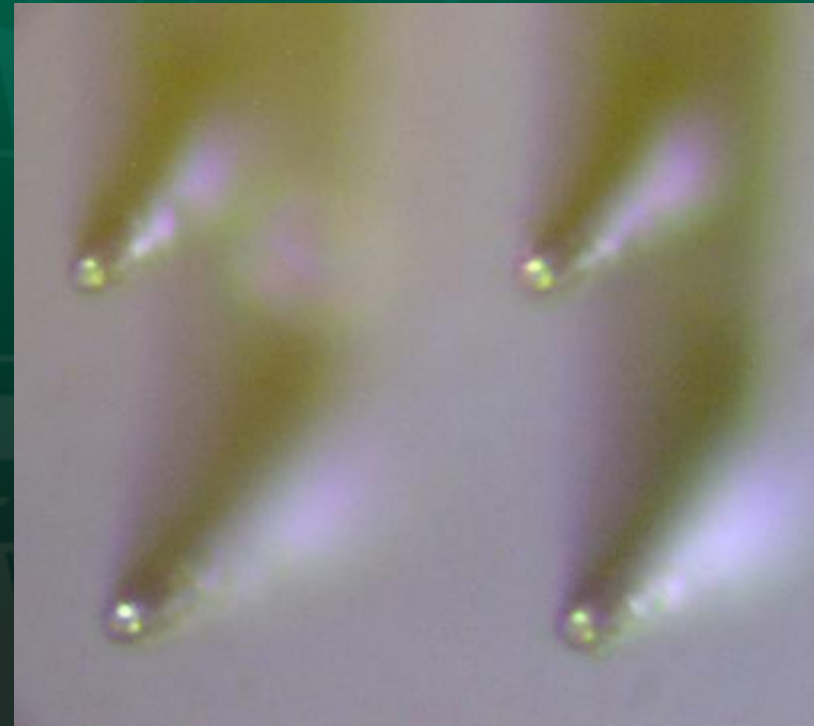
After Cleaning

Cleaning Test Result

- Probe Surfaces Before & After Cleaning (x50)



Before Cleaning



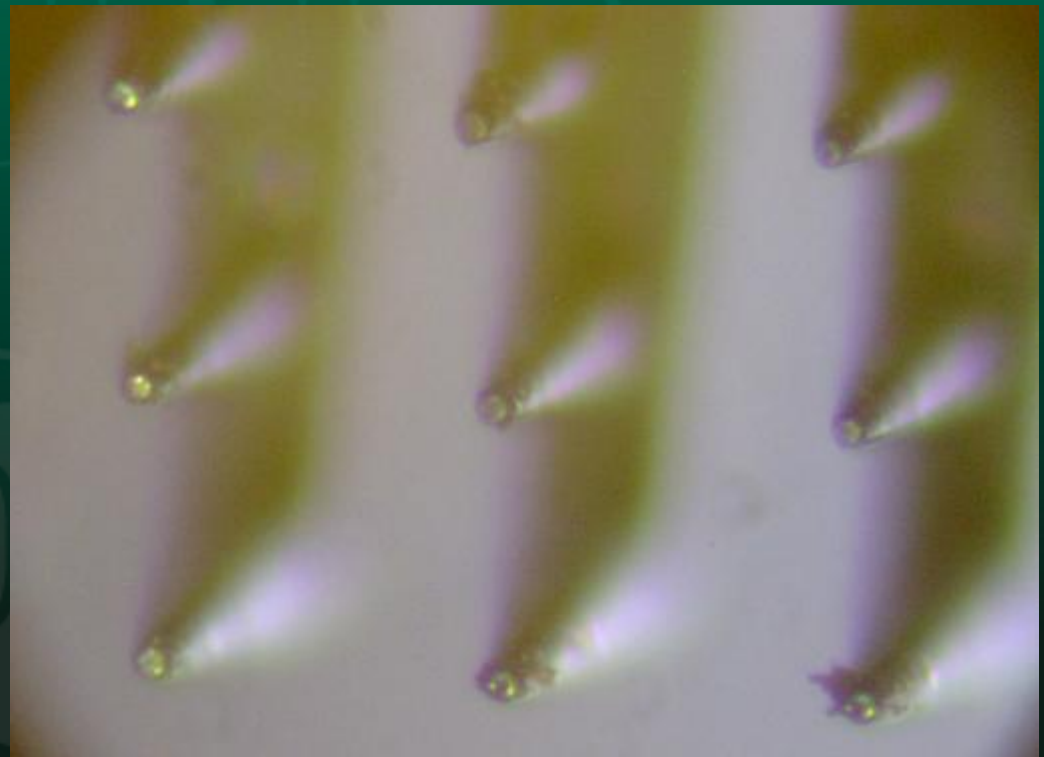
After Cleaning

Cleaning Test Result

- Boundary Region (x50)



F-G boundary region



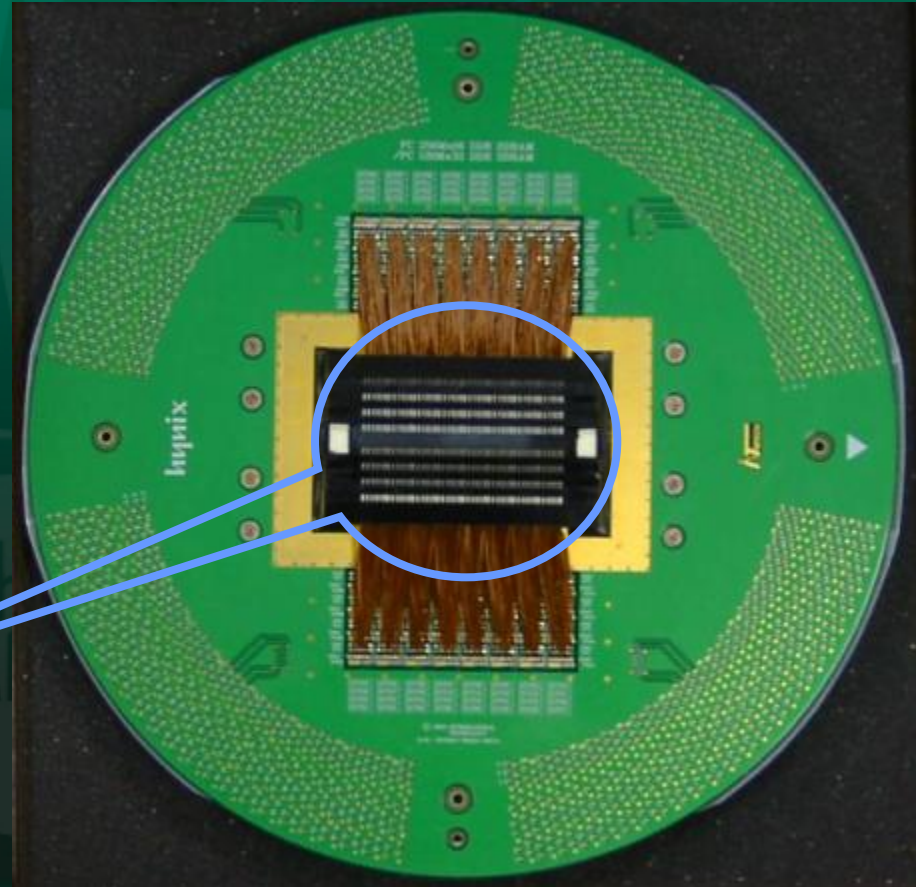
*Cleaned Area
(F-region)*

Uncleaned Area



4 Layer Cantilever PC

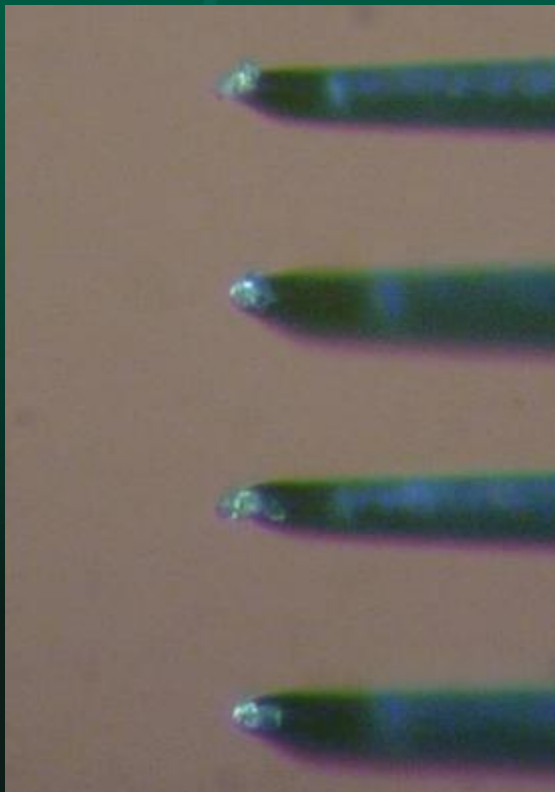
- Probe Card for IC driver chip



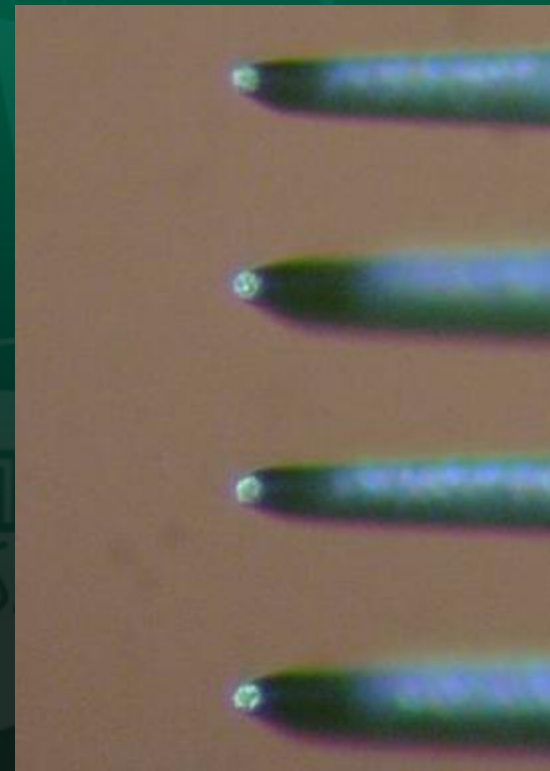
Cleaning Area

Cleaning Result (1)

- Probe Surfaces Before & After Cleaning (x50)



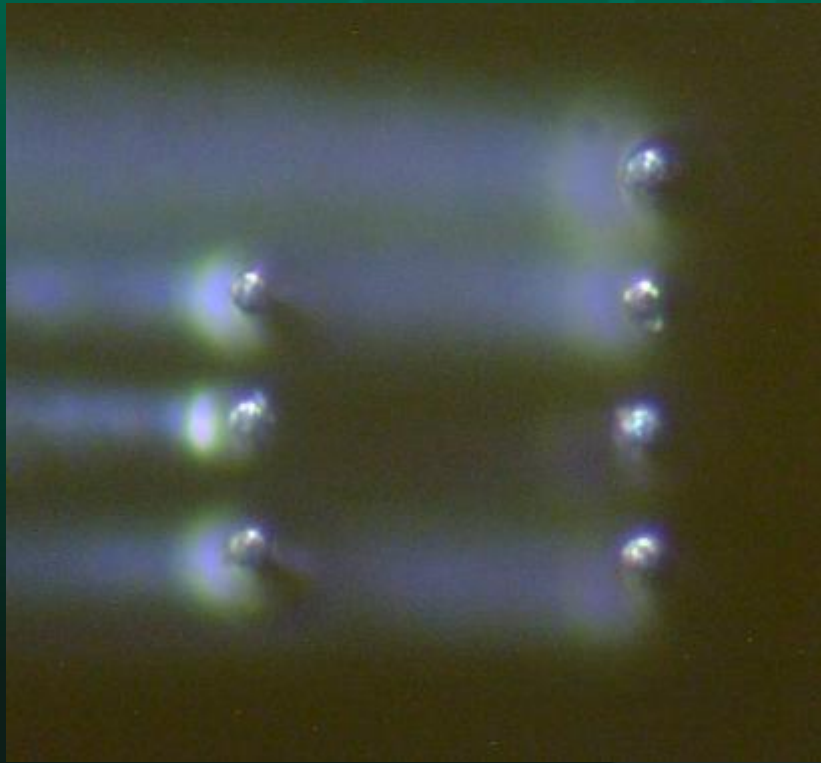
Before Cleaning



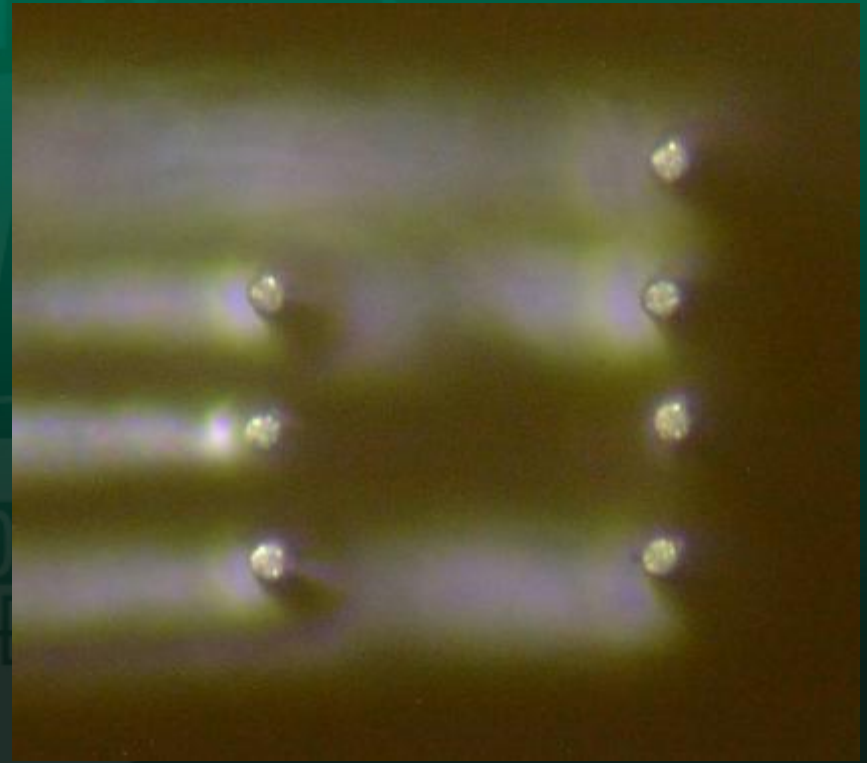
After Cleaning

Cleaning Result (2)

- Probe Surfaces Before & After Cleaning (x50)



Before Cleaning

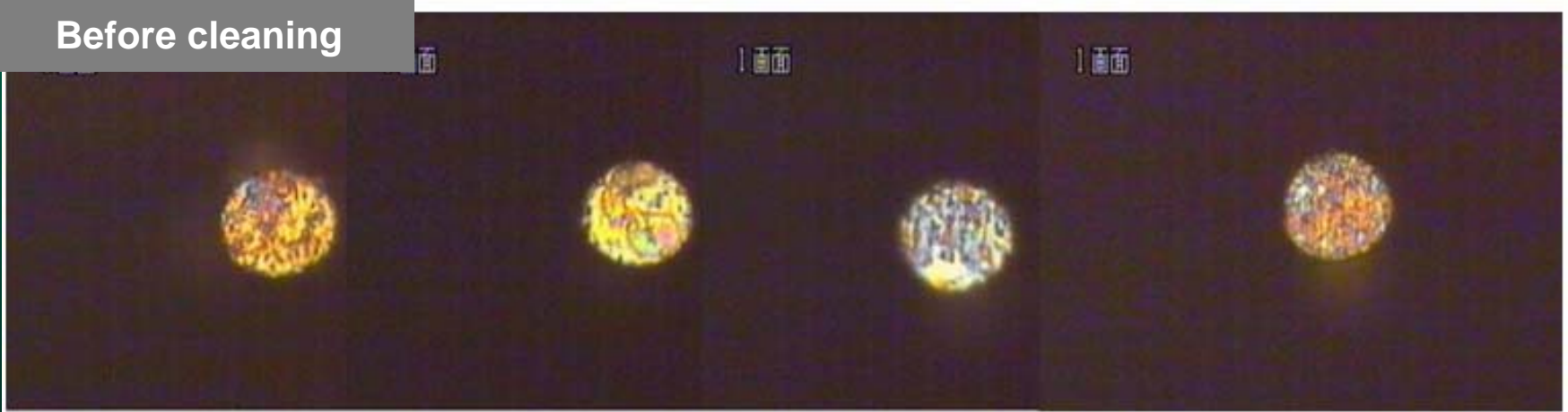


After Cleaning

Cleaning Result - details

- Magnified Tip Surface (x200)

Before cleaning

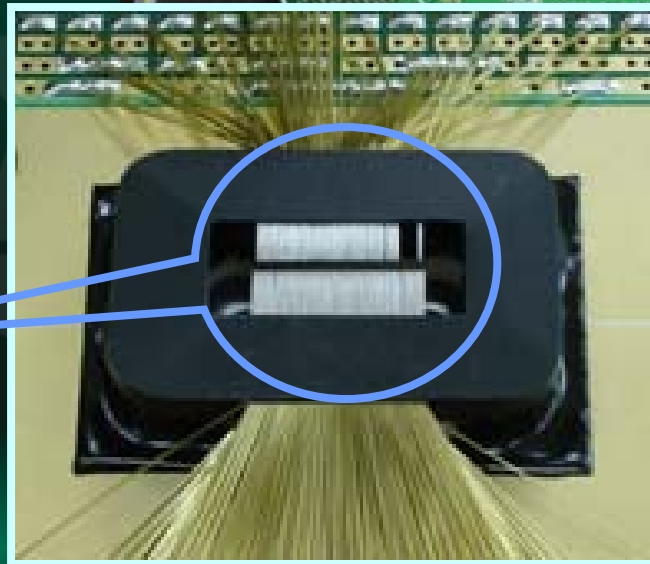
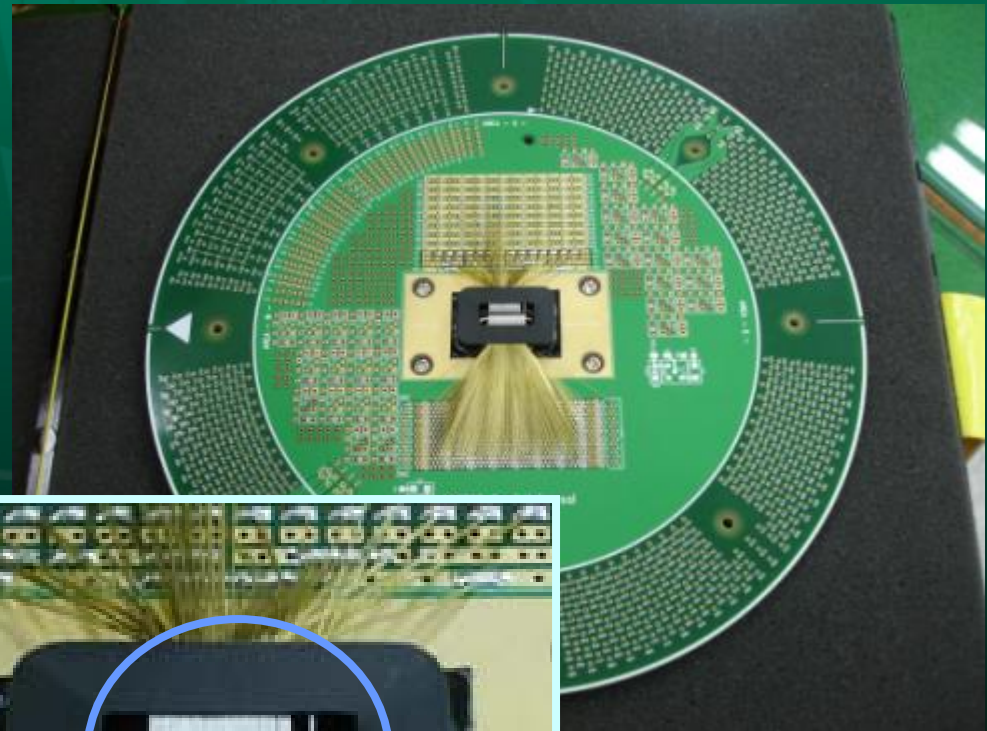


After cleaning



Cantilever PC – W-Pt

- W-Pt Probe Card for High speed performance

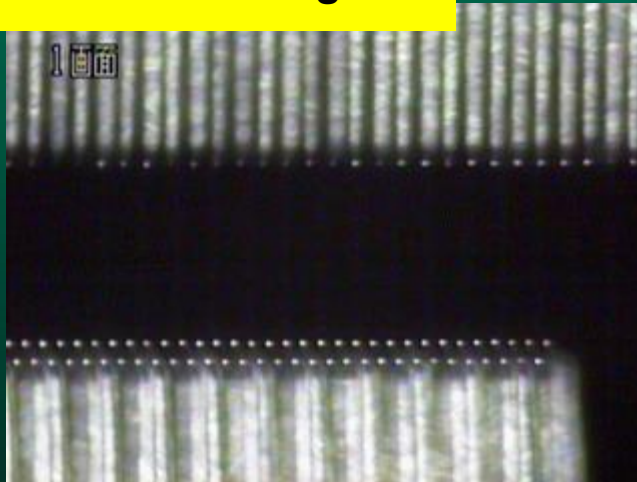


Cleaning Area

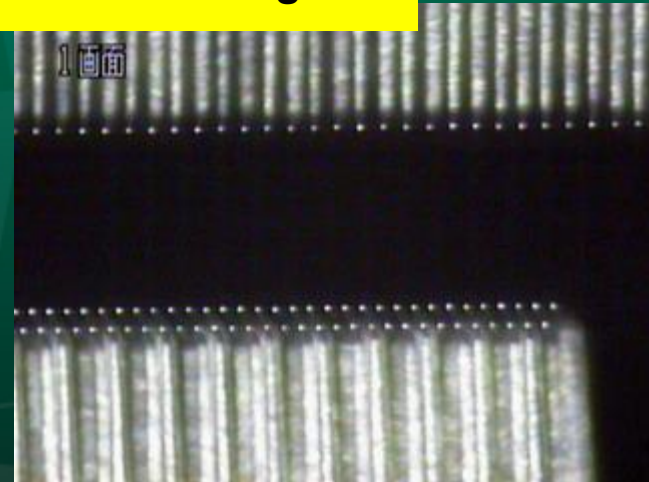


Cleaning Result



Before Cleaning



After Cleaning

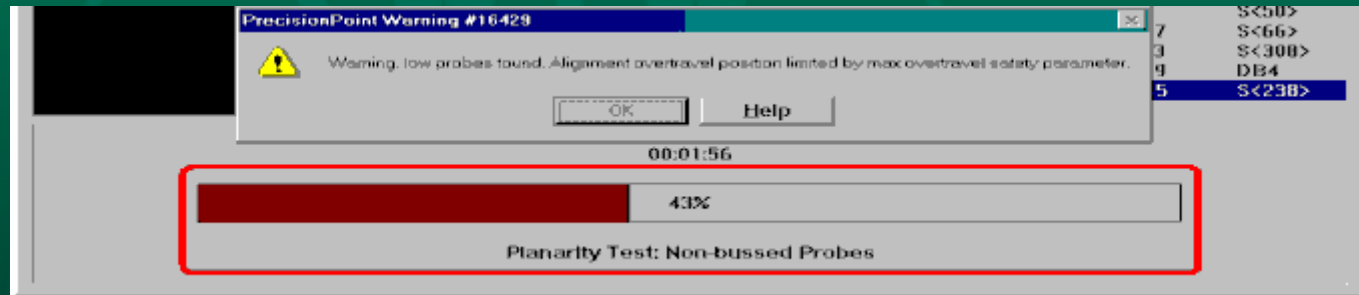


Electrical Test : Rc Measure

구분 Item	단면상태 Tip surface			PRVX3 Test [Contact Resistor]		
Before Laser Cleaning				Passed Failed Not Found	- - -	96 879 0
After Laser Cleaning				Passed Failed Not Found	- - -	577 398 0
Needle Diameter	Ø 80 μ m	Tip Diameter	7 \pm 1 μ m	Needle material	REW	
Laser 효과 effectiveness	Passed Channel 증가. C/R 저항 값 하락 Value decreased	PRVX C/R (Before cleaning)	1회 1.93~36.9 Ω 2회 0.10~31.1 Ω 3회 0.10~49.2 Ω	PRVX C/R (After cleaning)	1회	0.10~10.2 Ω
Laser	Power- 532nm Energy- 280mJ	Overtravel	Gold Plate - 20 μ m	PRVX C/R allowance	5 Ω	

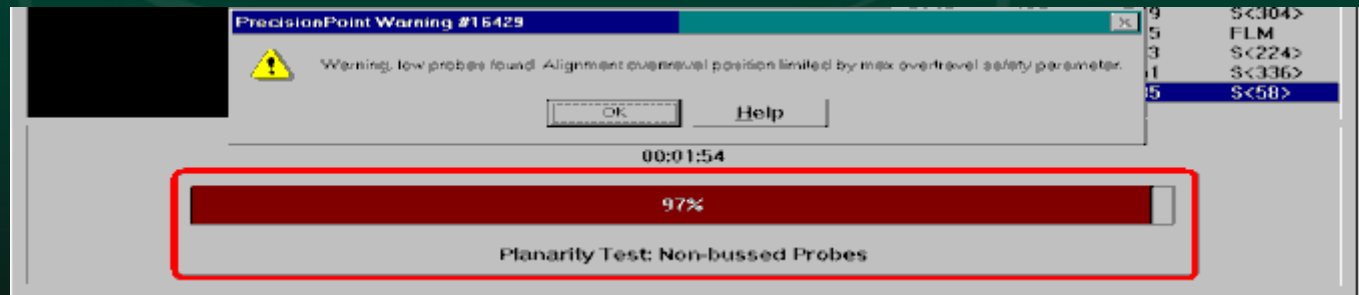
Electrical Test : Planarity

Before Laser
Cleaning
[사진 1.]



▪[사진 1.]과 같이 Tip의 산화 및 이물질 발생시 제품의 품질 저하 발생 Poor planarity data due to foreign contamination and oxides

After Laser
Cleaning
[사진 2.]



▪Tip의 산화 및 이물질 제거로 인해 [사진 2.]와 같이 제품의 성능 향상 효과 확인.

Improved planarity data after cleaning

■ Device

S6C Series [WillTech Co. Cantilever Probe Card]

■ Results

Planarity Pass Increased Significantly [Before cleaning: 43%, After: 97%]



Laser vs Sand Paper cleaning

第二階段P/C實驗結果

日期	型號	編號	測試機台	送修原因	處理方式	Leakage before cleaning	Leakage after cleaning	C/R before cleaning	C/R after cleaning	Time	上機可否使用
10/16	AW63602	PC097	TCV29	針髒汙	雷射	3	3	4.416	3.597	0950-1000	可
					手磨	1.1	1.5	4.629	4.021	2120-2130	可
10/16	TMT263J	PC403	TCV21	BIN3	Laser cleaning 雷射	5	5.7	7.752	7.609	1015-1030	可
					Sand paper cleaning 手磨	6.2	7.9	23.58	7.482	1410-1420	可
10/16	AN63601	PC387	TCV26	針髒汙	雷射	4.9	6.4	19.36	9.787	1045-1100	可
					手磨	3.4	5.7	25.76	6.396	1720-1730	可
10/16	FY63328	PC382	TCV04	BIN4	雷射	9.9	9.8	21.85	13.1	1115-1130	不可(針反白沒測)
				針反白	手磨	9.9	9.9	22.28	7.264	1205-1215	可
10/17	AN63601	PC447	TCV06	清針	雷射	6.5	7	7.074	6.147	1005-1020	可
					手磨	6.5	5.2	5.958	5.594	0505-0515	可
10/17	AW63602	PC445	TCV11	清針	雷射	3.3	3.2	8.976	6.709	1020-1035	可
					手磨	3.3	3.3	7.357	6.943	0535-0545	可
10/17	AW63602	PC360	TCV14	清針	雷射	2.2	2.4	6.977	6.61	1025-1040	不可(BIN9)
				BIN9	手磨	2.4	2.4	6.753	5.91	1100-1110	可

*** The CR improvement by laser cleaning is equivalent with the sand paper cleaning. Also there is no leakage problem after laser cleaning.



New PC Tip Cleaning -ReW

Before cleaning



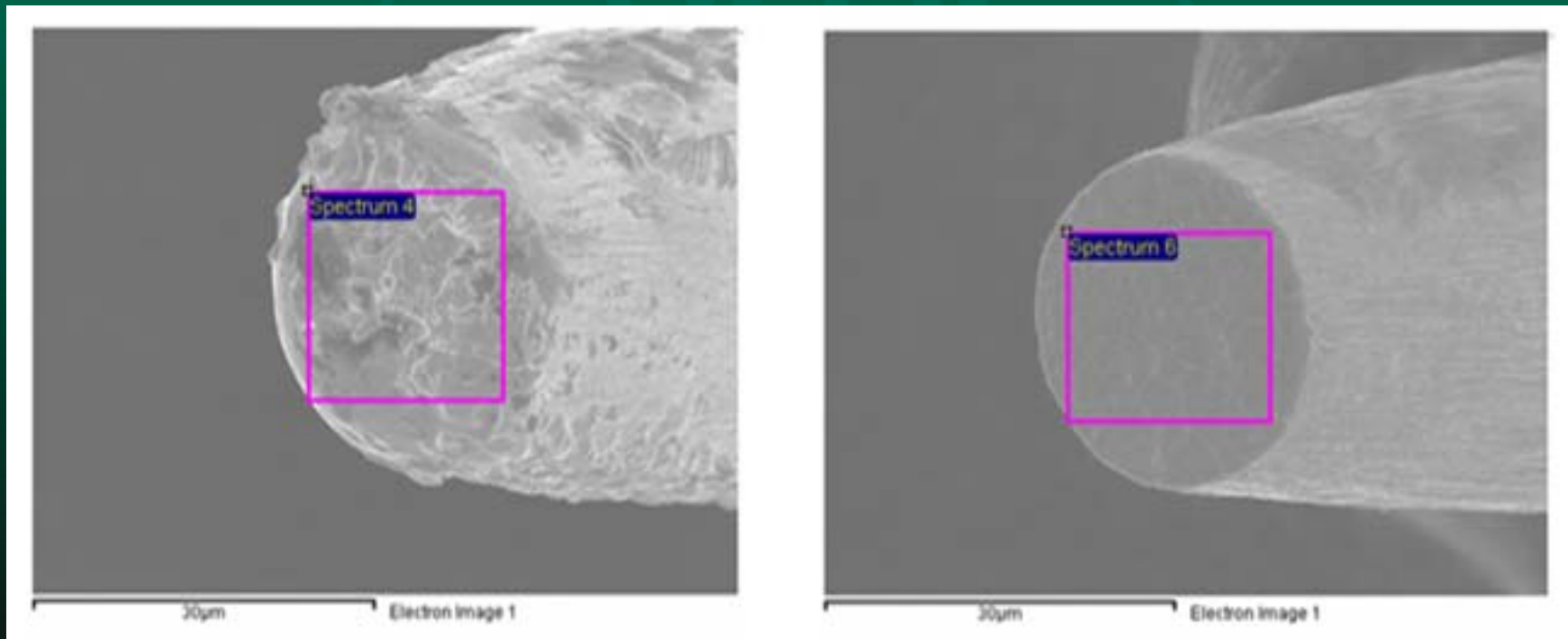
After cleaning



*** The original contamination on the tip such as organic and native oxide were successfully removed by laser cleaning.



SEM Analysis – New PC

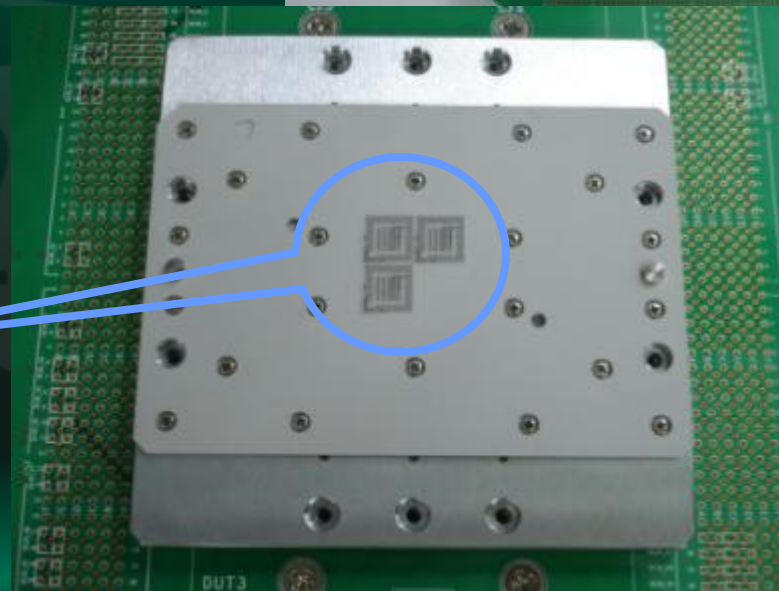
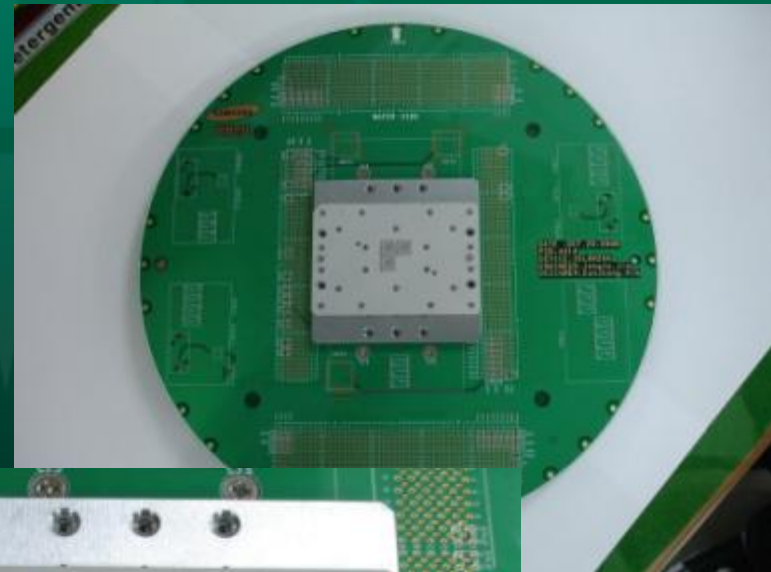


Before Laser Cleaning

After Laser Cleaning

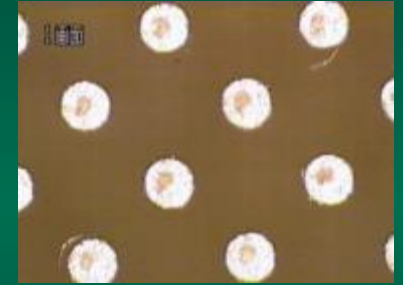
BGA Vertical PC

- E.Plastic Substrate & Vertical pins for Image Sensors
- Pin: Pd-Ag-Cu-Au-Pt



Cleaning Area

Test Result (1)



- Probe Surfaces Before & After Cleaning (x50)



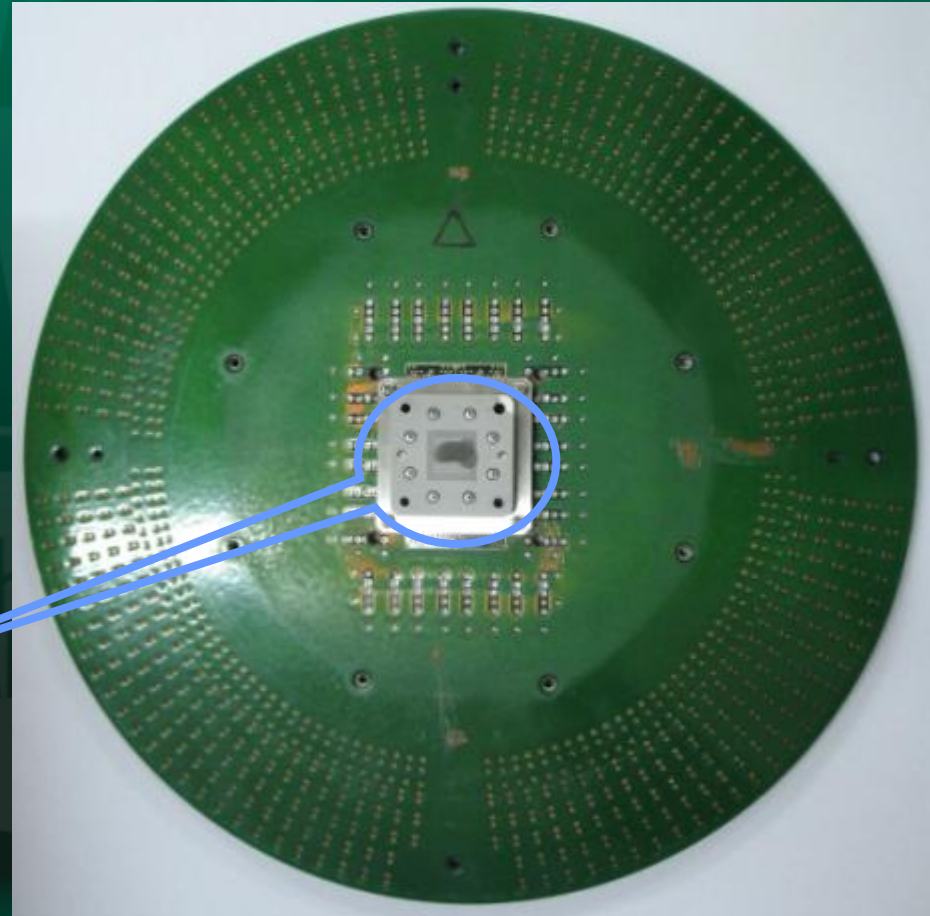
Before Cleaning



*After Cleaning
=> Well cleaned*

Pogo Pin Vertical PC

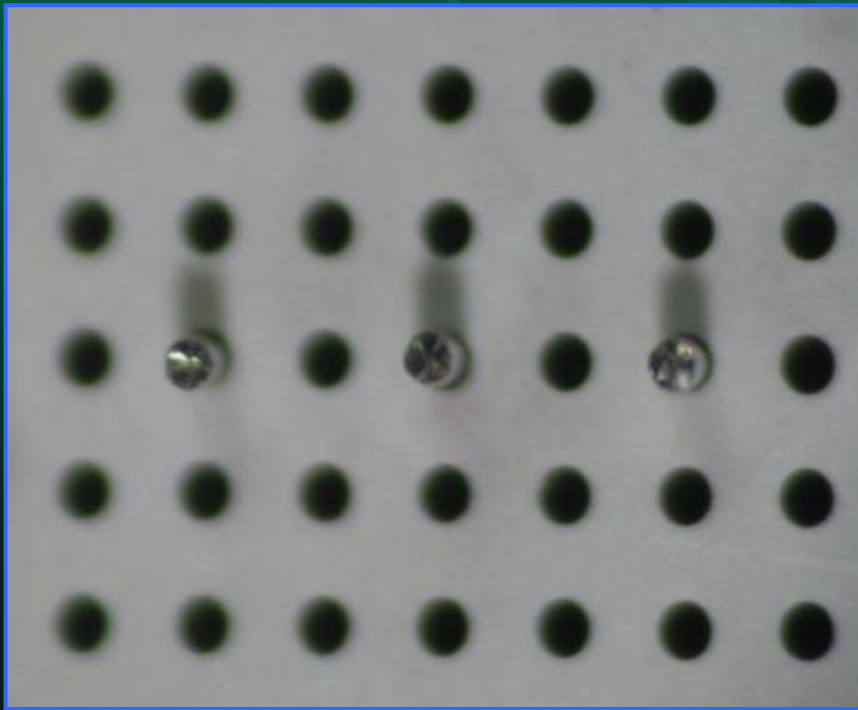
- Ceramic Substrate & Pogo Pin type Probe Card



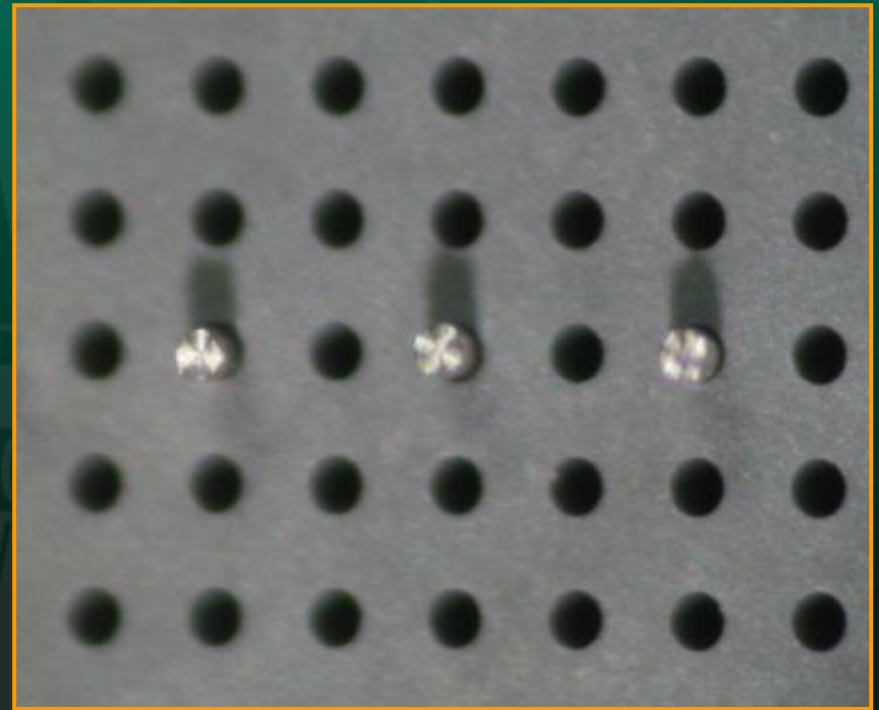
Cleaning Area

Test Result (1)

- Probe Surfaces Before & After Cleaning (x50)



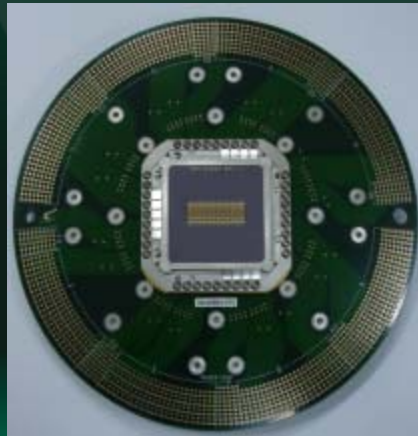
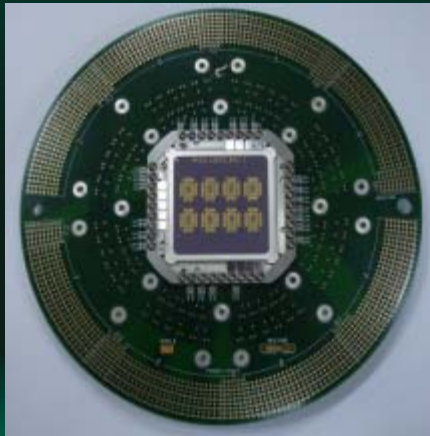
Before Cleaning



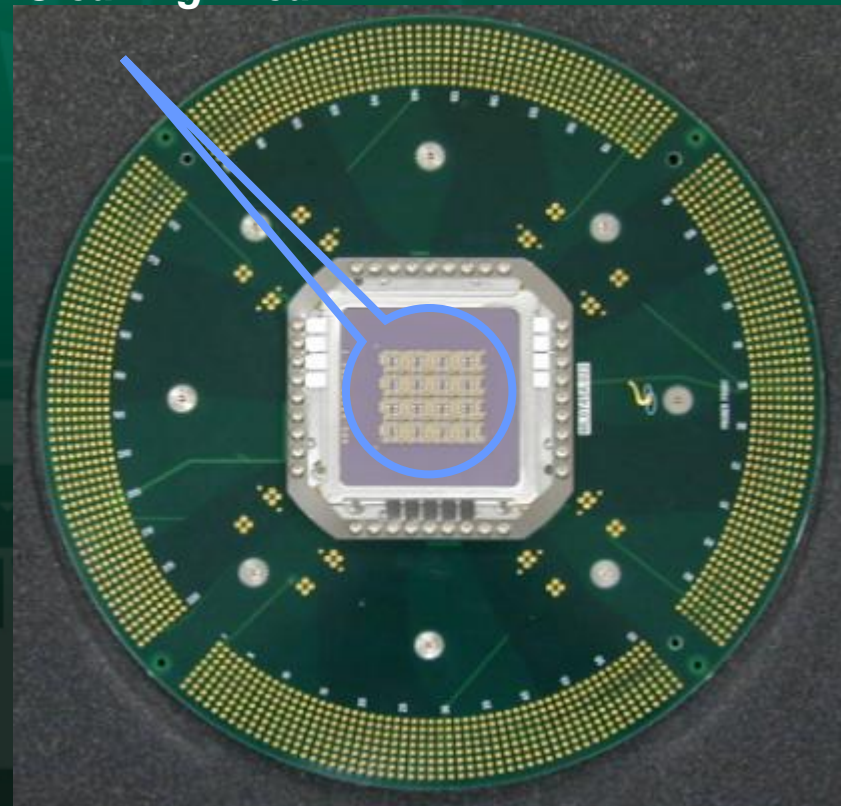
After Cleaning

MEMS P.C. – NiCo+Au

- MEMS Probe Card for IC driver chip (Foamfactor PC)

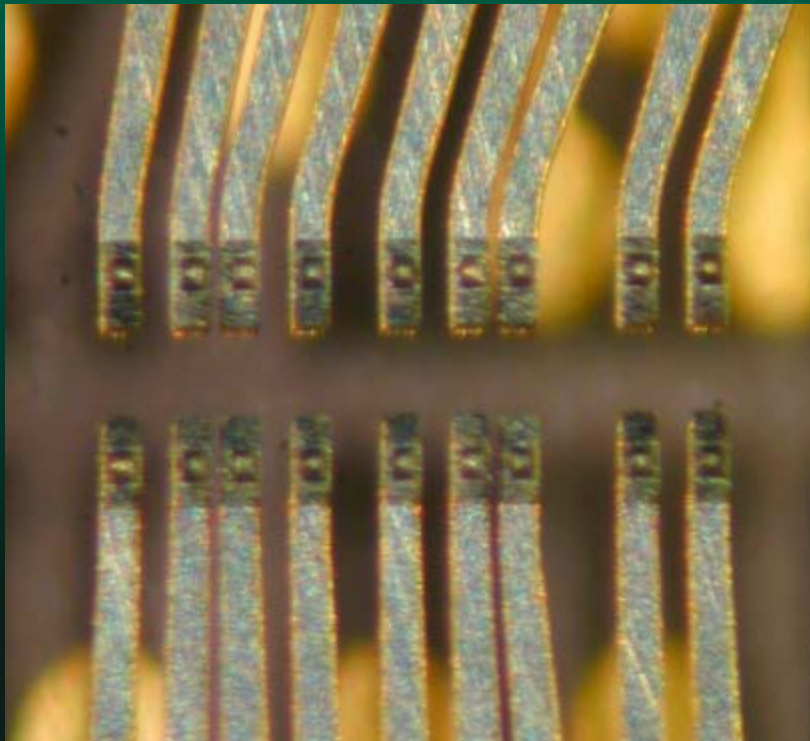


Cleaning Area

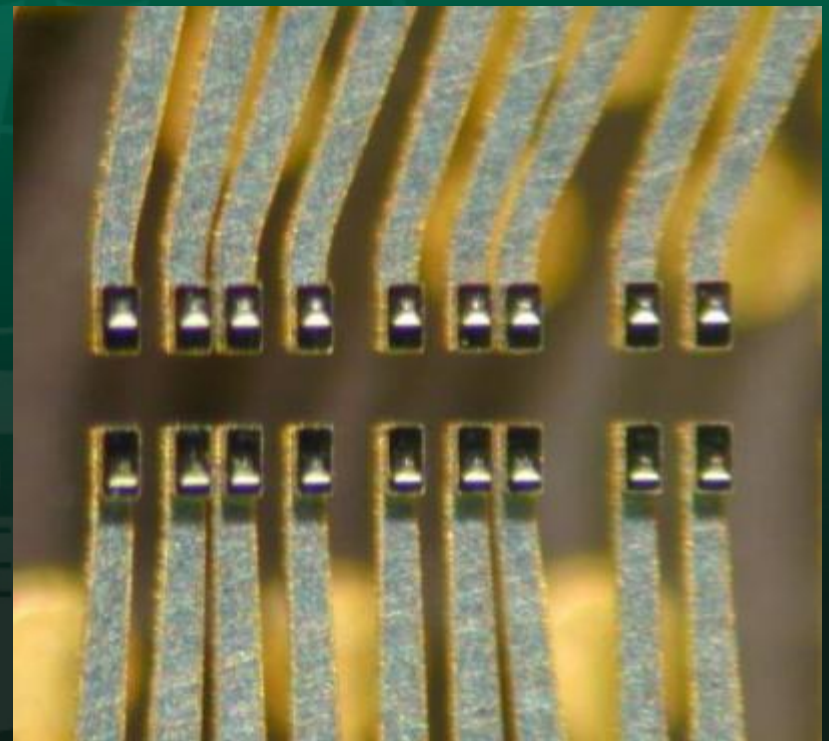


Test Result

- Probe Surfaces Before & After Cleaning (x50)



Before Laser Cleaning



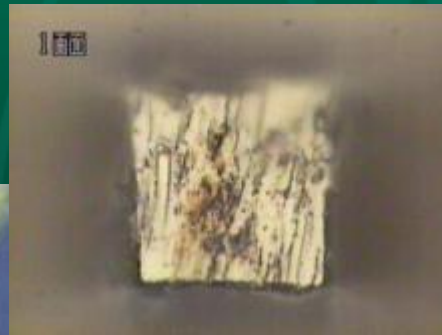
After Laser Cleaning



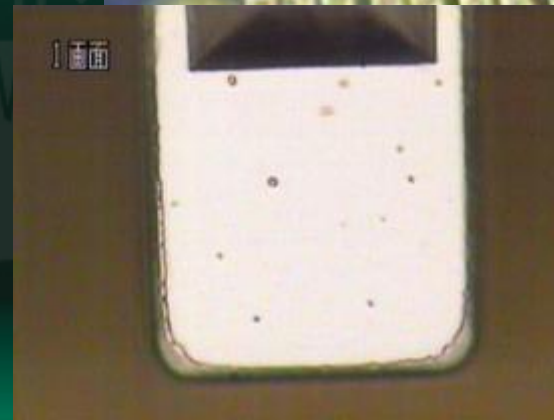
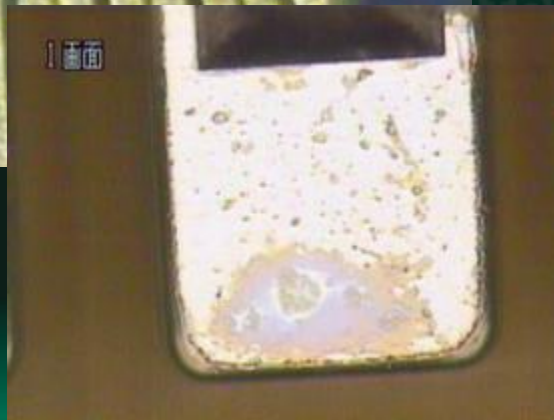
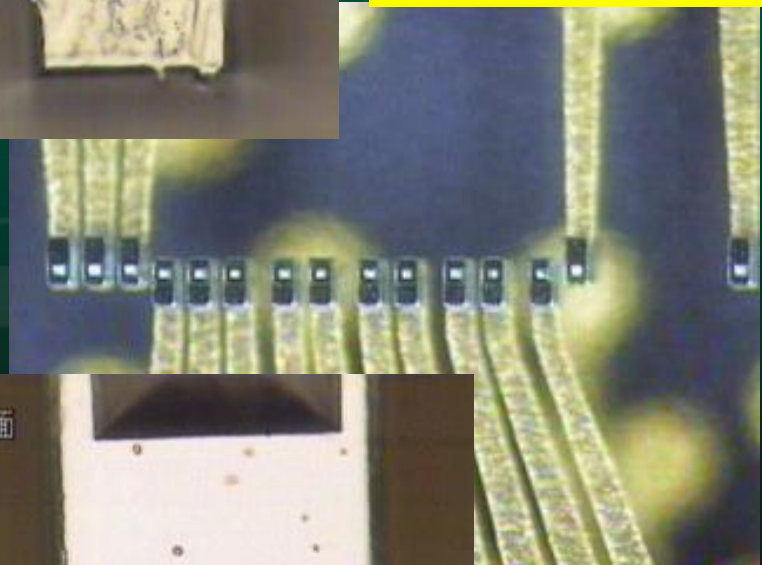
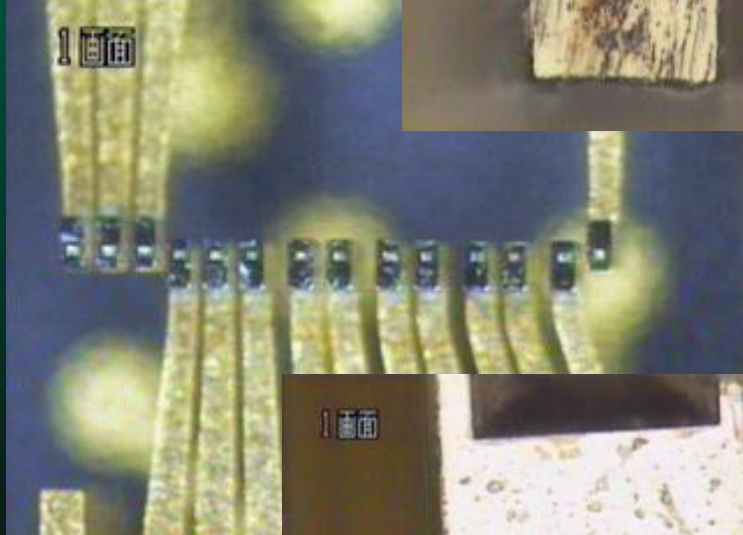
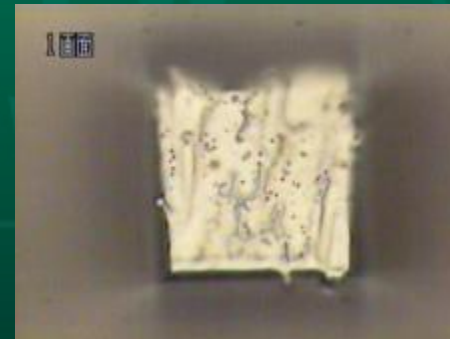
Test Result

- Probe Surfaces Before & After Cleaning

Before Cleaning

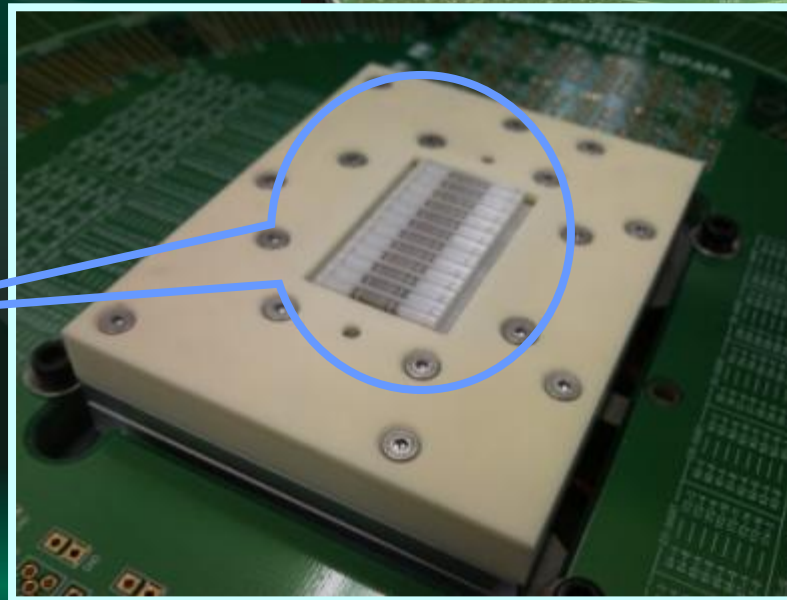
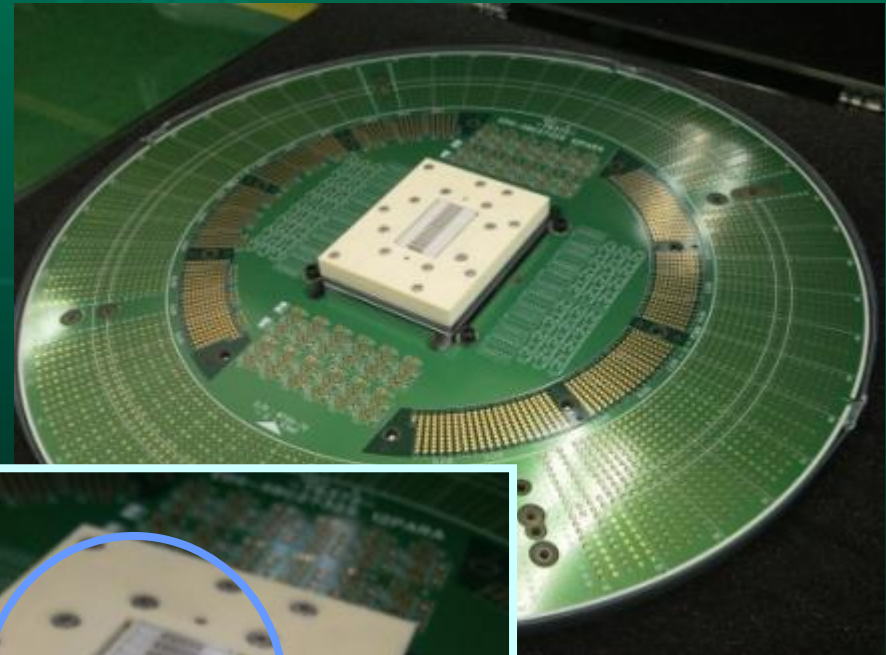


After Cleaning



MEMS P.C. - NiCo

- MEMS Probe Card for LCD Driver IC (LDI)



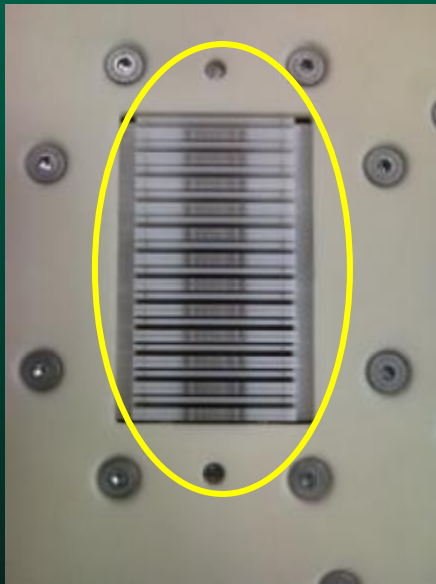
Cleaning Area



Cleaning Result

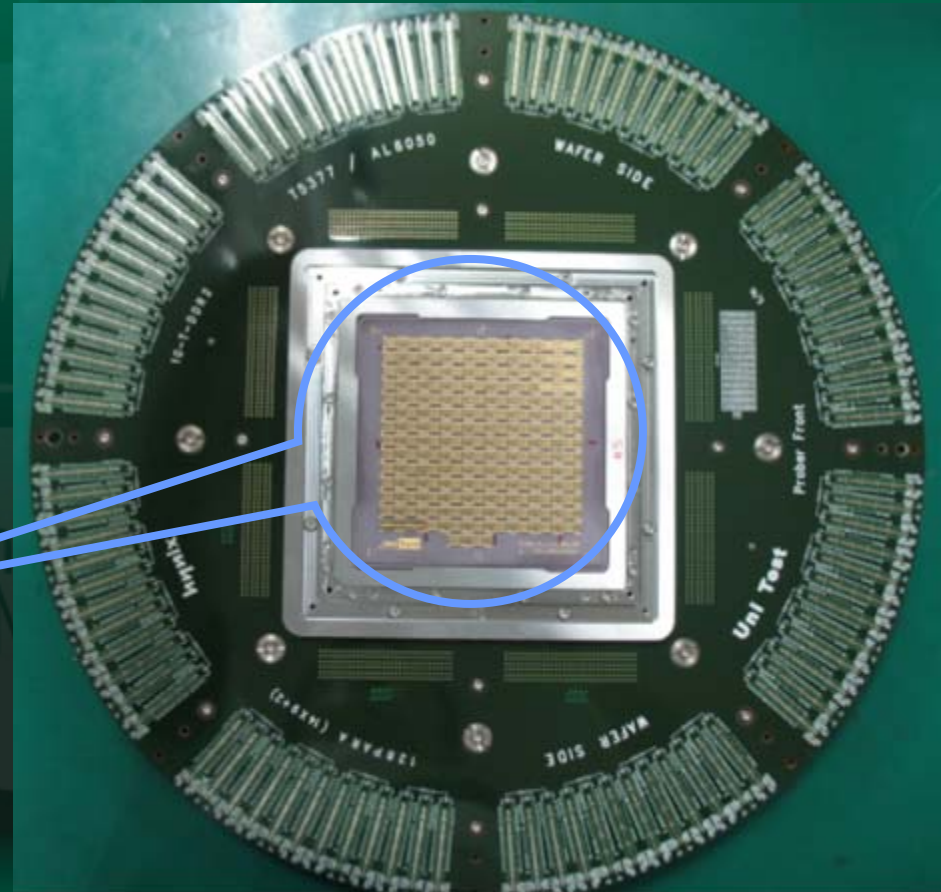
Before cleaning

After cleaning



MEMS P.C. - NiCo

- MEMS Probe Card for 1G DDR2 Memory (U-com PC)



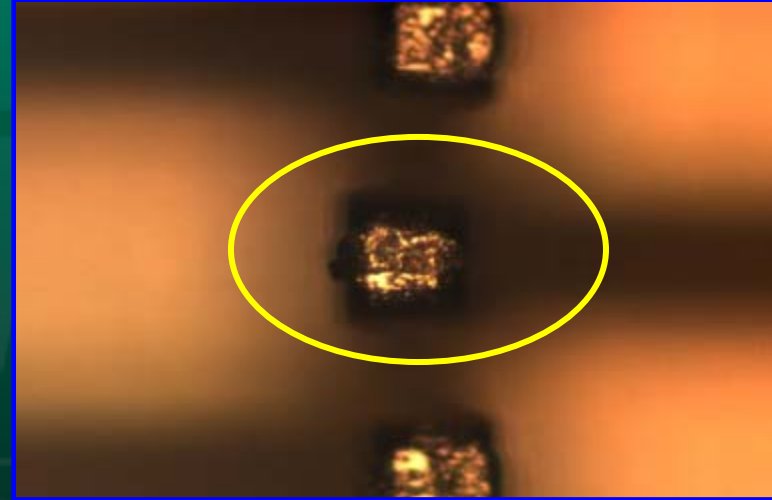
Cleaning Area



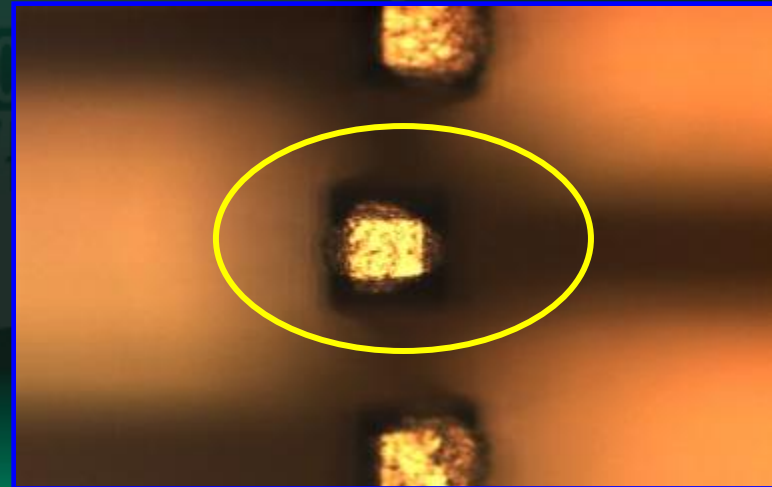
Cleaning Result



Before cleaning



After cleaning



Functional Results after cleaning

Before cleaning

			1.Alignment			2.Planarity	
Passed	-	-	796	796	796	965	-
Failed	-	-	953	953	953	90	-
Not Found	-	-	75	75	75	769	-
Pad	Leak	CRes	VXErr	VYErr	VAlign	Plan	Force

After cleaning

			1.Alignment			2.Planarity	
Passed	-	-	867	867	867	1755	-
Failed	-	-	957	957	957	40	-
Not Found	-	-	0	0	0	29	-
Pad	Leak	CRes	VXErr	VYErr	VAlign	Plan	Force

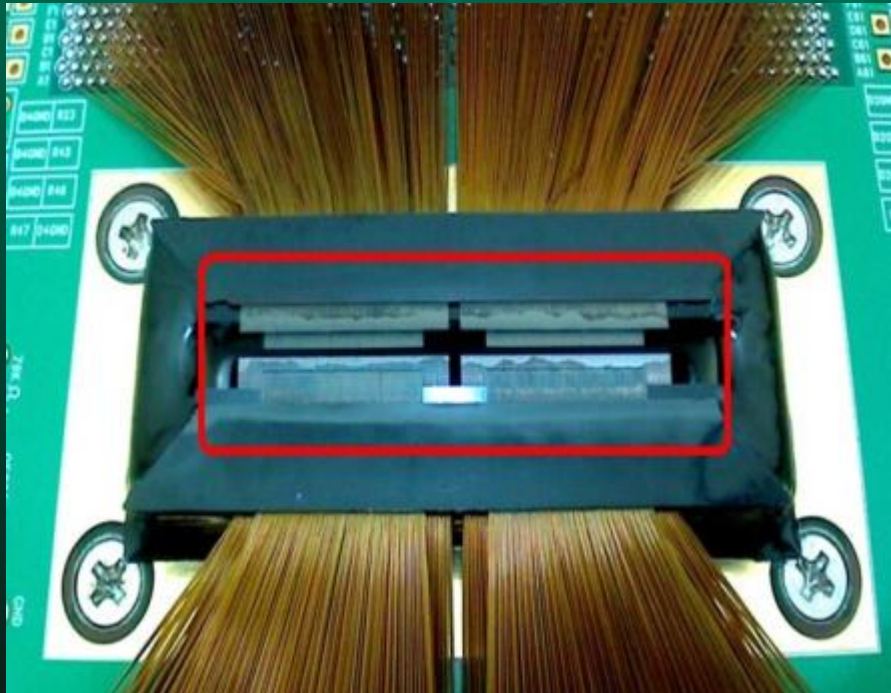
Alignment: "Not Found" 75 channels reduced and "Passed" increased by 70 channels

Planarity: "Not Found" 740 channels reduced and "Passed" increased by 790 channels.

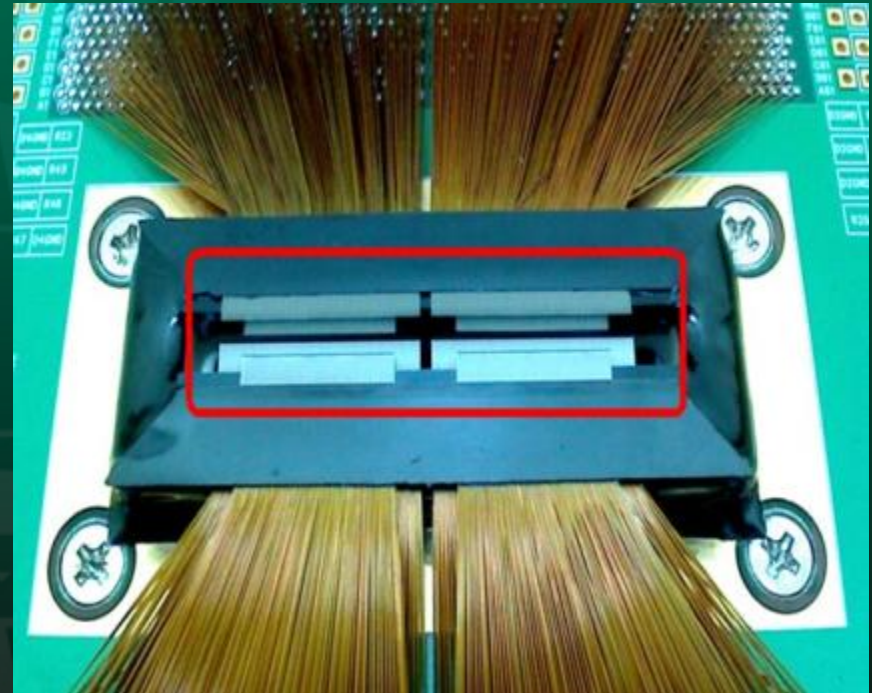
>> Very effective of Laser cleaning for MEMS probe card



Needle Body Cleaning



Before Laser Cleaning

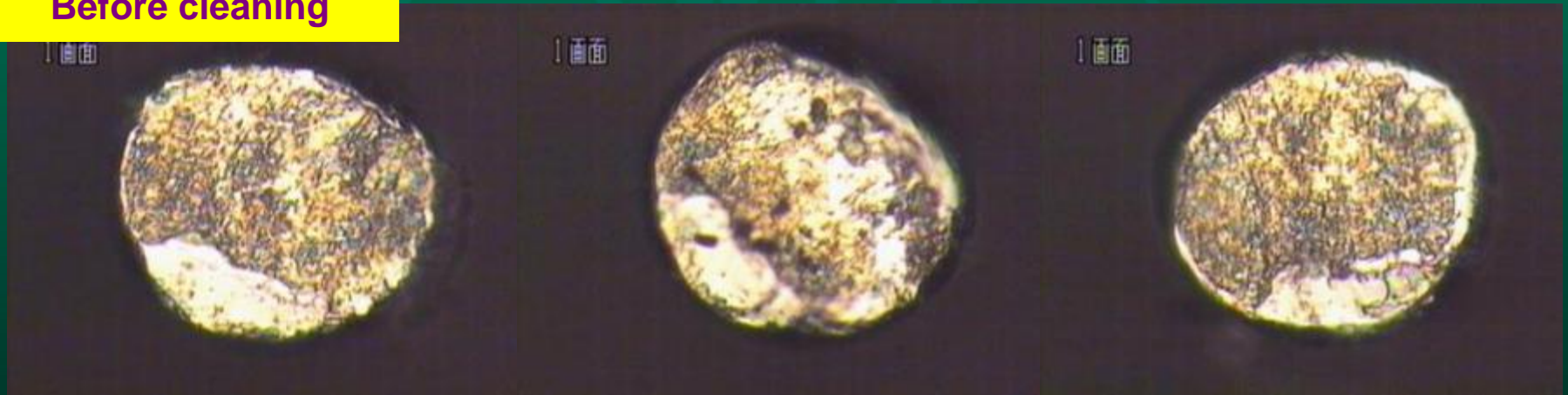


After Laser Cleaning



Cobra Needle Cleaning (Pt)

Before cleaning

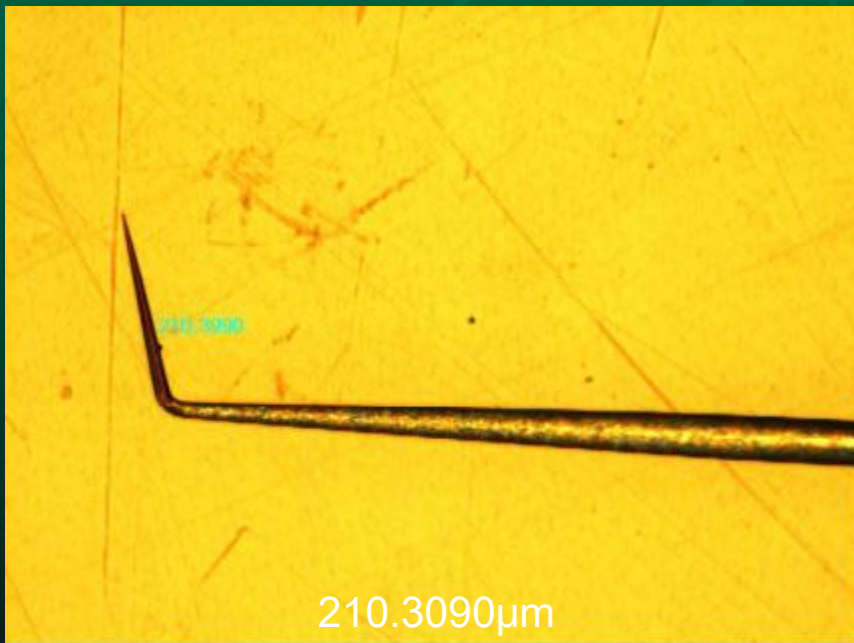


After cleaning

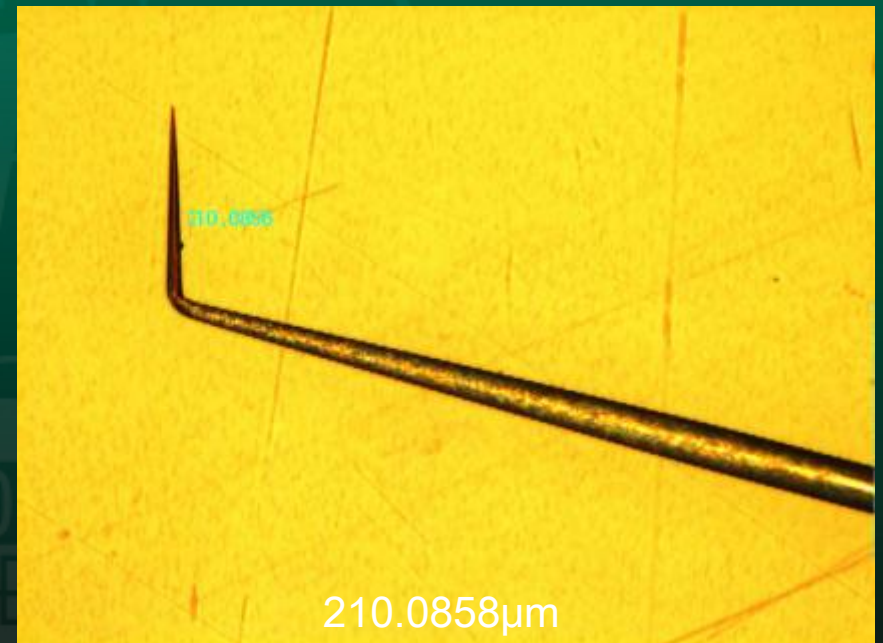


Damage Test - Dimension

- ◆ Probe dimension before & after 1000 laser shots at 350mJ



Before Laser Cleaning

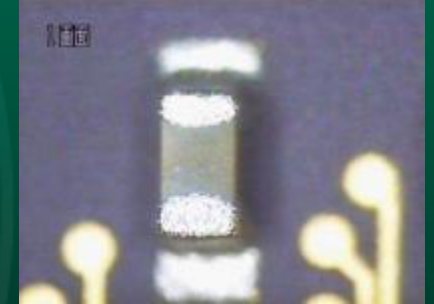
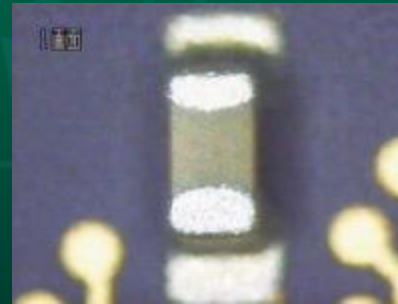
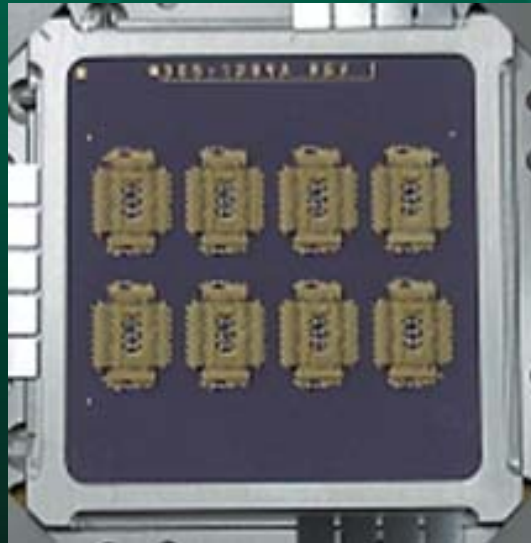
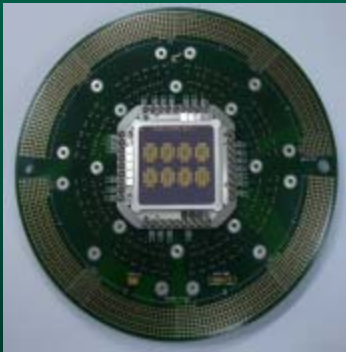


After Laser Cleaning

*** There was no any dimensional change after 1000 times of laser cleaning => No physical damage by laser

Damage Test - Substrate

- ◆ Substrate & Parts before & after 100 laser shots at 350mJ



Before treatment

After treatment

*** There was no any surface changes after the harsh 100 laser treatment => No physical damages by laser cleaning

Commercial Tools – Laser Cleaner



*** Mobile & Manual
For on-line cleaning

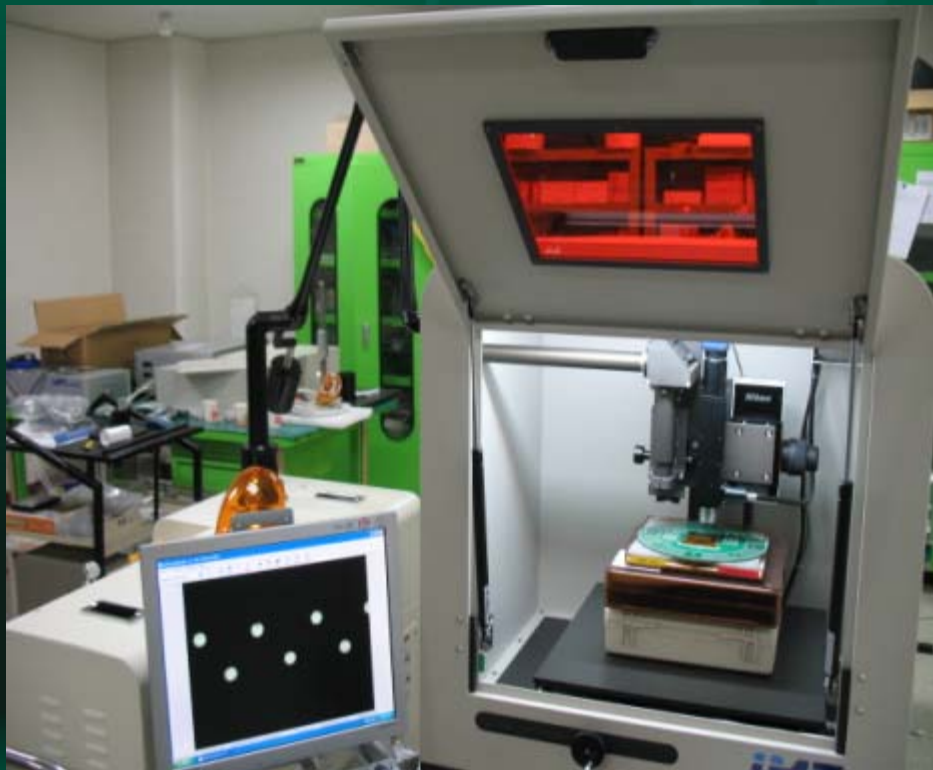


*** Fully Automatic
For off-line cleaning



Real Application – X-Y Cleaning Stage

- * Off-line Cleaning Stage
- Manual operation



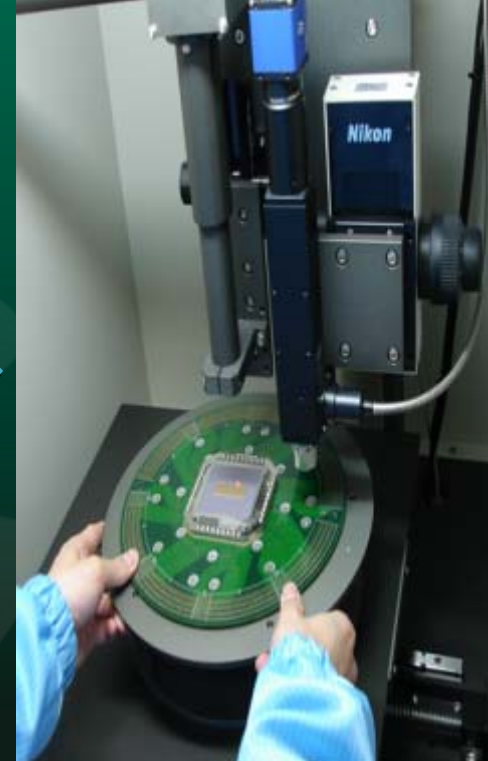
PC Cleaning Process (1)



Laser Cleaning
Parameters Setting.



Install PC onto the
cleaning stage



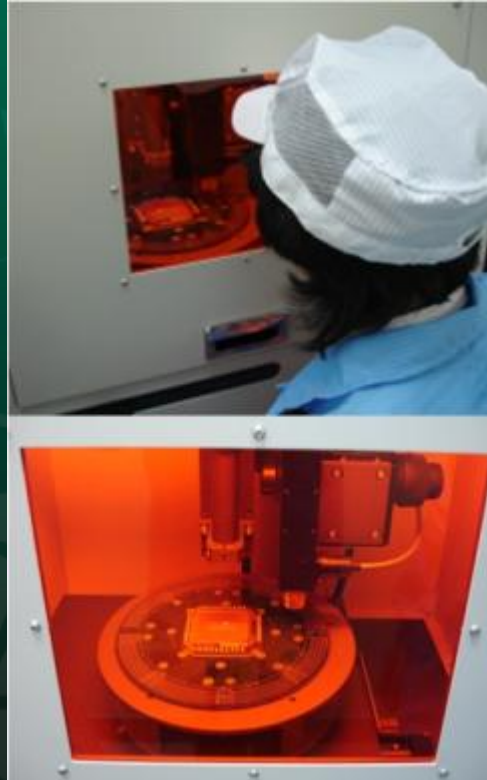
Positioning PC to
the laser beam
pointer



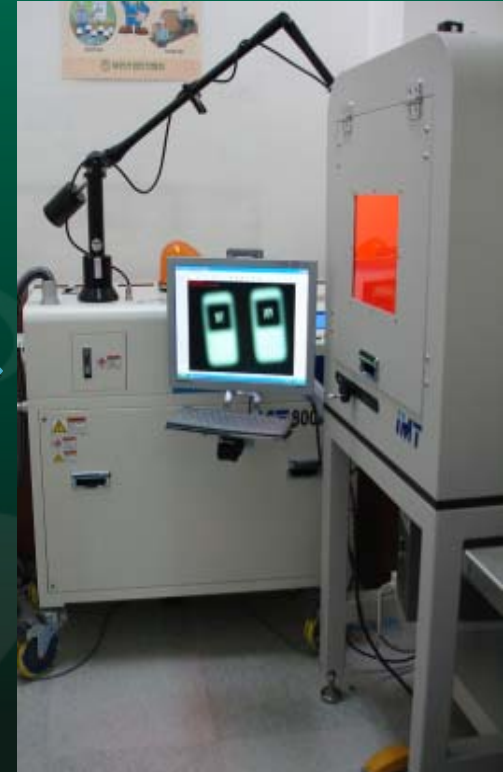
PC Cleaning Process (2)



Close the door and
PC Cleaning start



X-Y Manual PC Laser
Cleaning



Checking the
cleaning quality by
vision camera



Summary & Conclusions

Laser cleaning can be applied successfully for :

1. Canti: W, Re-W, W-Pt ...
2. Vertical: Au in BeCu(pogo), Pd-Ag, Pd-Co ...
3. MEMS: Au in Ni-Co, Ni-Co ...

=> **Without any pin & substrate damages**

Laser cleaning can provides :

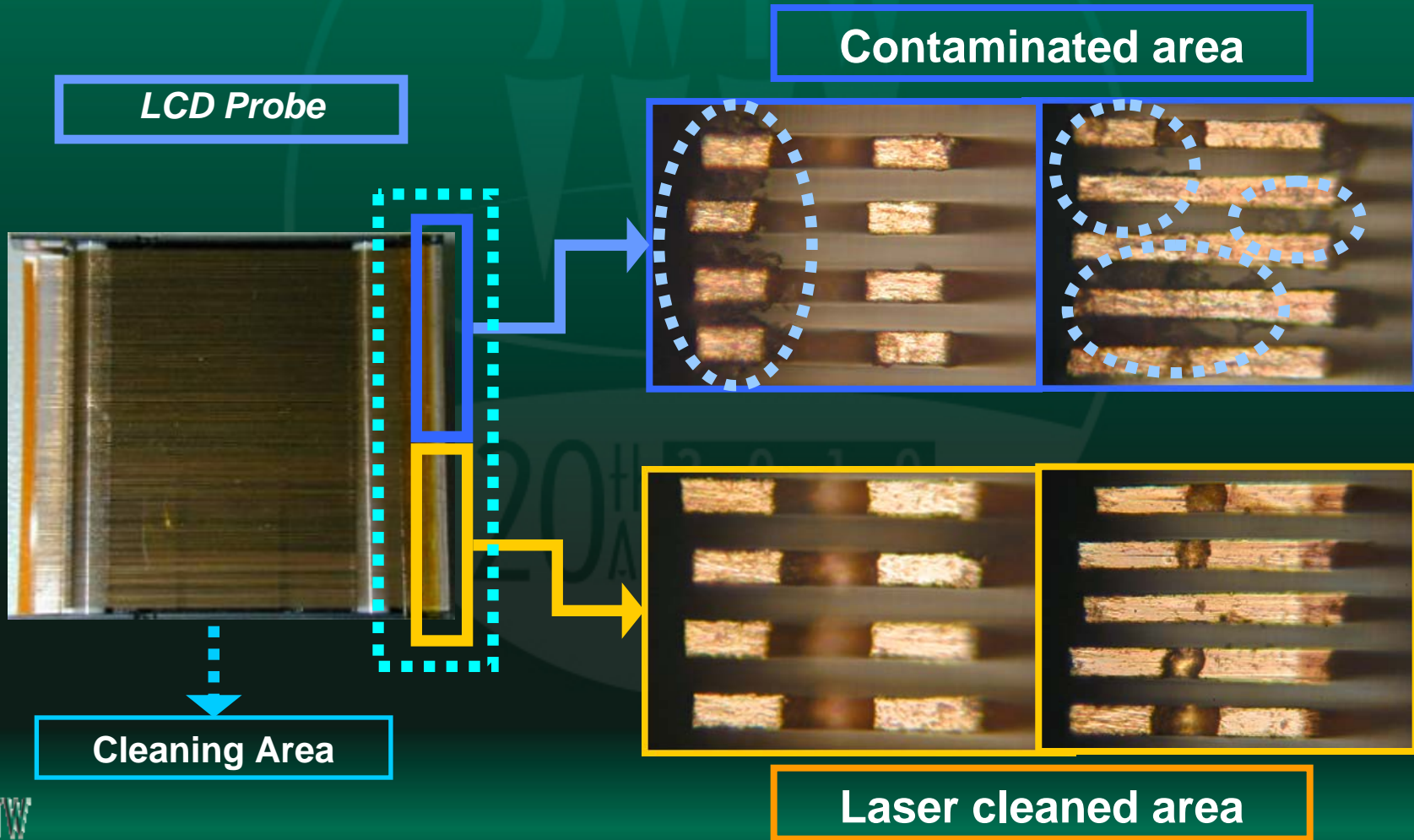
1. High speed cleaning even for 300mm PC
2. Safe cleaning even for MEMS PC
3. Quality assurance even for New PC

=> **Novel Probe Card cleaning solution**



LCD Probe Cleaning

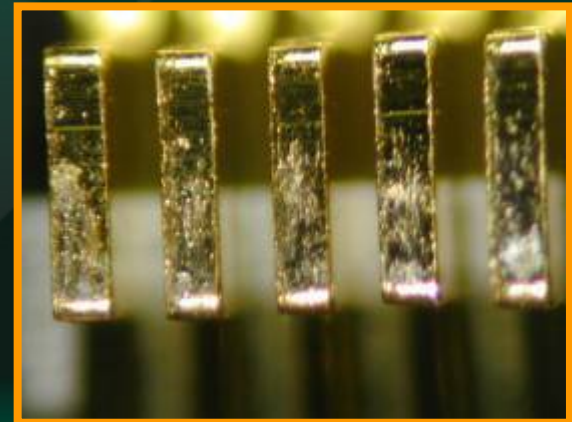
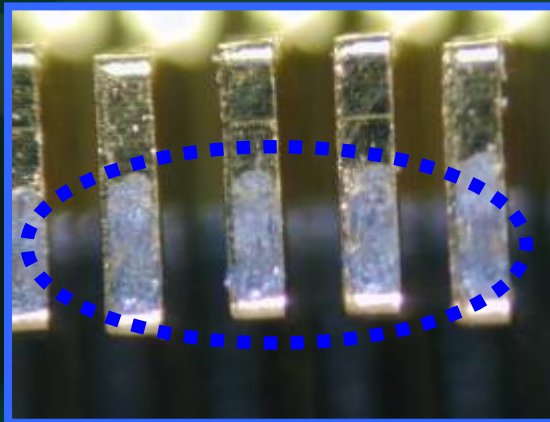
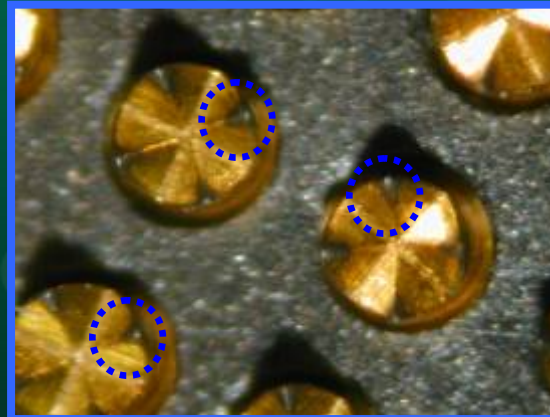
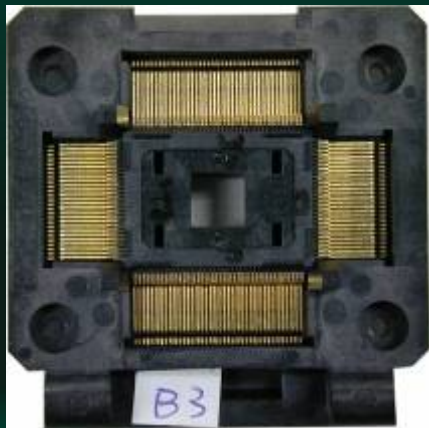
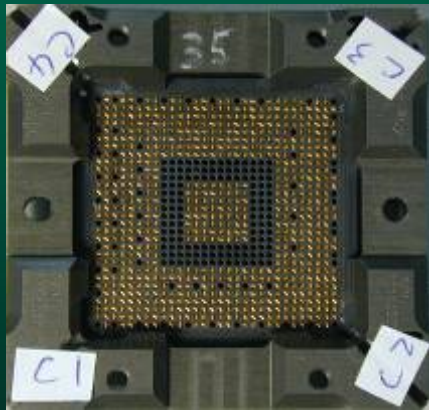
- Probe Surface Before & After Cleaning (x200)



Test Socket Cleaning

■ Target of Test Socket Cleaning

: To remove Tin(Sn) based contamination from pogo-pin surface

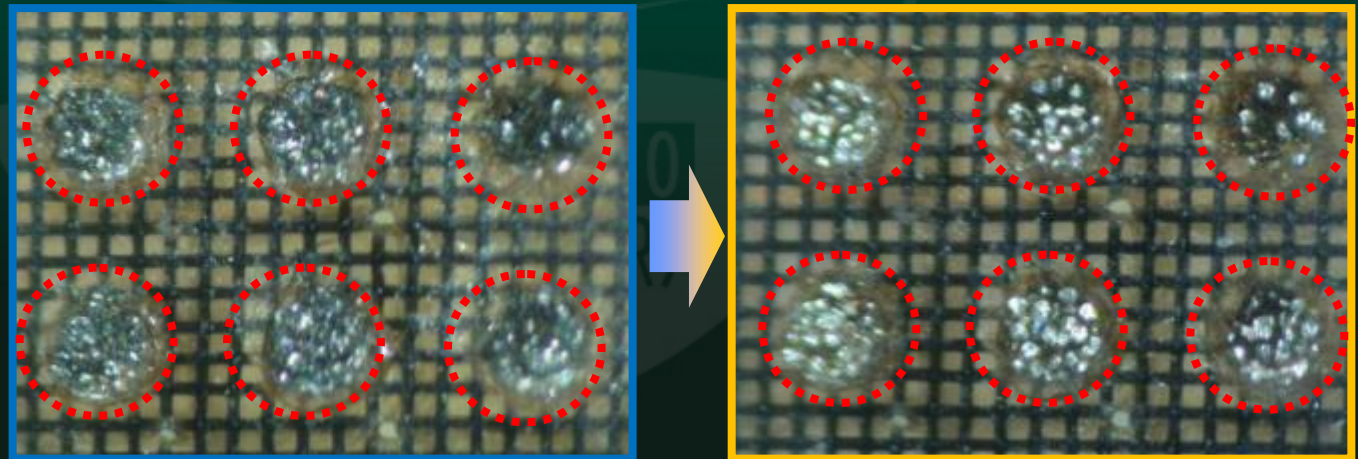
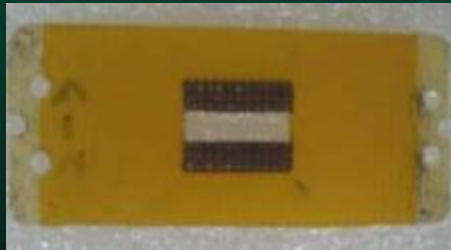
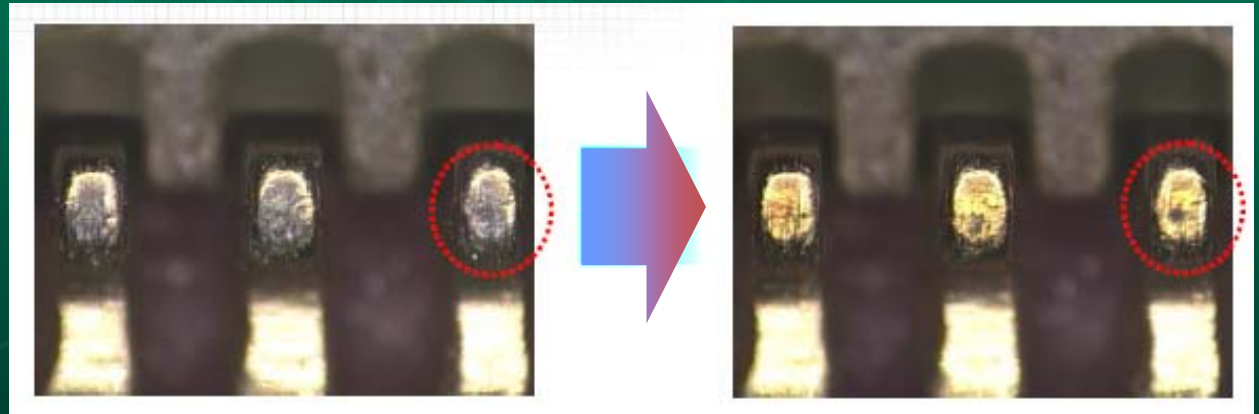
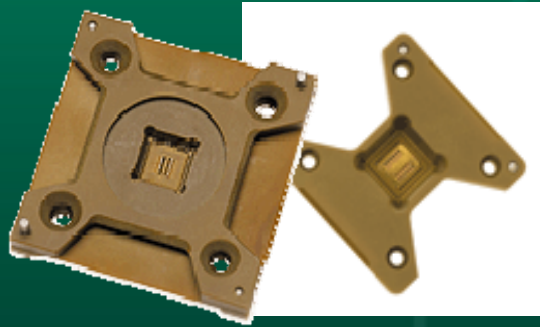


Before cleaning

After cleaning



Test Socket Cleaning



Before cleaning

After cleaning

